REVIEWS OF TOPICAL PROBLEMS

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Nanotribology: experimental facts and theoretical models

G V Det kov

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<u>Abstract.</u> Nanotribology is a new physical discipline in which friction, adhesion, wear and lubrication are studied within a unified framework at the nanoscopic level. In this paper, the experimental and theoretical problems of topical interest in this field are reviewed. In the analysis of the experimental data, emphasis is placed on 'dry' adhesive friction between the probe of a scanning frictional microscope and an atomically smooth surface. On the theoretical side, studies related to the mechanisms of adhesive (static) and dynamic (velocity proportional) friction are discussed and results on the electromagnetic, electron, and phonon effects as well as molecular dynamics results are presented. Studies using the method of quartz crystalline microbalance and the 'surface force' concept are briefly reviewed.

1. Introduction

The study of the nature of friction forces on the atomic level was made possible with the advent of the atomic force microscope [1, 2]. In a decade, rapid progress in this fund amentally new method of physical investigation lead to the establishment of vast new field of physics — nanotribology — which combines experimental and theoretical studies of

G V Dedkov Kaba¢ ino-Balkarian State University, 360004 Nal'chik, Russian F¢ eration Fax (7-095) 337-99 55 E-mail: gv_d ¢ kov@rekt.kbsu.ru

Receivér 17 July 1999, revisér 5 March 2000 Uspekhi Fizicheskikh Nauk **170** (6) 585–618 (2000) Translatér by V M Matveev; ér itér by S D Danilov $a^{\hat{t}}$ hesion, friction, wear and lubrication, chemical activity and triboelectromagnetism on the nanostructural level [3–11].

Only recently, problems associated with friction were for the most part of an engineering character and might be thought of as $\dot{\alpha}$ irty' physics, since the macroscopic contacts of surfaces in the literal sense are $\dot{\alpha}$ irtised by absorbed particles, wear products and lubricants. However, as was often the case in science history, what only yested ay seemed to be archaic, to ay takes on a new meaning — and now one can say without exaggeration that the off scienced ealing with friction (tribology), the found ations of which were lad $\dot{\alpha}$ own by Amonton three hund red years ago, has received a second birth.

An und erstand ing of the key role of numerous ind ived ual microcontacts appearing between contacting surfaces has given impetus to the d evelopment of nanotribology. The total area of such contacts (the area of actual contact) can be much less than the apparent area [6, 12].

With the transition to a qualitatively new level of investigation, it turner out that physical processes in tribocontacts are consirt erably more intricate and $\hat{\sigma}$ iverse than har been suspecter and include a wealth of new phenomena such as phase transitions resulting from the shear or ering of thin films in the 'probe-surface' contact and the formation of contact 'bridges' [4], chemical, electrochemical and triboelectrical effects [13–15]; effects associated with humer ity [16, 17], superconductivity [18] and so on.

Along with atomic force microscopy (AFM) and friction microscopy, experiments carried out with the use of surface force apparatus [4, 19, 20] and the quartz crystal microbalance technique [21–23] occupy an important place in the studies of nanotriboeffects. These experimental method s presently hold the greatest promise for nanotribology. The

rapů ly progressing surface nanoin entation technique may be also assigned to these method s.

Scanning tunnelling microscopy (STM)^d evelope^d before AFM [25] organically combines with the latter, since most present^d ay probing microscopes operate in the multime^d e regime inclu^d ing both STM and AFM me^d es.

The stur y of friction and processes associated with it on the nanostructural level is of great interest for a broad spectrum of technical applications such as the technology of production and surface coating of hard magnetic d isks for computers, the fabrication of microsensors and so on. These and the traditionally important engineering applications of tribology in machine construction require a d eeper insight into the properties of materials on the atomic level with the aim of optimizing and forecasting the tribological characteristics of friction surfaces. Successful solution of these problems calls for d ecreasing the existing gap between the macro- and nanostructural levels of knowled ge of the properties of material in general and friction in particular.

Unfortunately, experimental information in the field of nanoprobing microscopy and tribology has accumulated so rapid ly that the theoretical d escription of many effects still remains unsatisfactory, even though a number of important recent results were successfully predicted and /or interpreted using the molecular d ynamics (MD) method and classical contact mechanics. Although d ry' friction d oes not d epend on the visible area of a contact and practically d oes not d epend on the slip velocity, its seeming simplicity is d eceptive, since it is d etermined by a complex d iversity of properties of surfaces, by the presence of numerous microcontacts, effects of an ad hesive and d eformative nature as well as 'ploughing' of the surface with microroughness and wear prod ucts.

There exist several levels of complexity in the effort to $un\dot{d}$ erstand the nature of $a\dot{d}$ hesive friction — the most intricate and least known mechanism. One of these levels is associated with the necessity of eveloping ad etailed atomic theory of triboprocesses d escribing ad hesion, friction and wear using an unified approach within the framework of the atomic mod els of chemical bond ing and elementary electron – phonon processes responsible for energy issipation.

Another level concerns the slip mechanism. For the present we are not in a position to state whether the relative movement of contacting surfaces is continuous or a series of d iscrete events of sticking and slipping. If the second scenario is realized, what are the values of the displacement and time interval corresponding to an elementary microslip? Many experimental works point to the fact that the stick-slip effect exhibits lattice period icity [3] enabling one to obtain the atomic contrast of a surface in the lateral AFM more. However, it is possible only in the case of atomically smooth surfaces, whereas most often the contact area is contaminated by a sorbe substances and wear products. These causes result in the existence of a gap between experimental and theoretical nanotribology. There also exist some problems of an instrumental nature which d o not always allow one to make an a equate correlation of theoretical models with experiment (for example, the problems of calibration of experimental results).

The main aim of this paper is to make a critical analysis of the experimental and theoretical results obtained in this new field over the last five or six years, although some of the problems concerned have been elucidated to a greater or lesser extent of completeness by a number of foreign authors [3, 11, 26]. At the same time, an attempt is made to construct some integral physical picture specific to nanotribocontacts the elementary areas of friction. Many results presenter in this paper have not yet been $\dot{\sigma}$ iscusser in the literature, and efforts to systematize theoretical notions are of a fragmentary character, since the basic calculation more els are still und er $\dot{\sigma}$ evelopment and there is no commonly accepter point of view on some of these more els. This concerns problems relating to the interpretation of the stick-slip effect, ad hesive friction more els, the $\dot{\sigma}$ ynamical mechanisms of noncontact friction and so on.

On the whole, ind ecd ing on the problems to bed iscussed in this review, both its restricted volume and the subjective viewpoint of the author have und eniably contributed. Therefore, in particular, when discussing theoretical models, much attention is given to the problem of try' at hesive friction and noncontact (ynamical) friction in vacuum. An und erstand ing of these elementary processes brings us nearer to an und erstand ing of the nature of friction as a whole. The 'ploughing' effect, 'wet' friction, the thermot ynamical aspects of the problem and ad iversity of other questions call for special consideration. Some of these questions are partially $\dot{\sigma}$ iscusse in works [25-30]. It should also be note that, though the main line of evelopment of nanotribology is associated with the application of probing microscopy, the d iscussion of the method s and results of the latter is not the subject of the review and is presented only in connection with the const eration of tribology problems.

The review has the following structure. Section 2 is a brief review of the basic mot es of operation of the AFM and other method s user in experimental investigations of micro- and nanocontacts. In Section 3, on the basis of the available experimental d ata, some physical processes in tribocontacts such as the stick-slip effect, at hesion, chemical and other effects ared iscusser. The existing theoretical notions providing an interpretation of experimental at are considered in parallel. On the whole, this part of the review is of a d escriptive character, and it end s with the formulation of some important experimental problems facing specialists in the field of tribology.

Section 4 is entirely $\dot{\sigma}$ evote to theoretical motels. It begins with the d iscussion of the contact-mechanics approximations and their use for interpretation of AFM d ata on $\dot{\alpha}$ ry' $\dot{\alpha}$ hesive friction in vacuum. Then the simple mot els of the lateral movement of a probe providing an interpretation of the experimental images of a surface are construct, and the evolution of the structure of nanocontacts observer with the use of the molecular dynamics method is discussed in d etail. Furthermore, the mechanisms of static (velocityind epend ent) and d ynamic (velocity-proportional) friction are const ered, the application of theoretical models to the explanation of the experimental dependences friction force – load ing force', the stick-slip effect, the effect of amping the at sorbet -film movement in quartz crystal microbalance experiments and so on is analyzed. Other theories, for example, the theory of rubber friction with a stiff surface are d iscussed more briefly.

Section 5 is concerned with applications of the results of nanotribological investigations in presented ay technologies. The 'probe-surface' interaction allows one not only to $\dot{\sigma}$ etermine the structure of the contact area on an atomic scale, but also to more ify the properties of a surface. In particular, the portions of the tunnelling contact of a probe with a passivated silicon surface und ergo selective oxel ation. This makes it possible to perform nanolithography irectly in

the mode of contact scanning. To reduce processing time, it is necessary to increase the scanning spect up to 1 cm s^{-1} . There is no question that the achievements of scanning probing microscopy, nanotribology and nanotechnology are capable of leading to a revolution in microelectronics in the near future.

2. Basic modes of operation of atomic force microscopes

Following pioneer works by Binnig et al. [1] as well as Mate et al. [2], the AFM technique has gaine i lear ing positions in stur ies of nanostructural friction. Forces acting between a sharp probe (tip) place in close contact with a sample and the surface of the latter result in a measurable of eformation of a cantilever (console) to which the probe is attacher. Fig. 1a illustrates a wir ely user more of operating the AFM on the basis of optical d etection of the probe position. Other methor s are d escriber, for example, in works [30, 31] (see also references in Ref. [3]).

The cantilever bend s in the vertical $\dot{\mathbf{d}}$ irection upward s or $\dot{\mathbf{d}}$ ownward s because of a repulsive or attractive interaction, and the value of its $\dot{\mathbf{d}}$ eformation is $\dot{\mathbf{d}}$ irectly proportional to the value of the counterpoising elastic force. The lateral forces result in torsion $\dot{\mathbf{d}}$ eformation relative to an equilibrium position. When the system is at equilibrium, the forces, which are responsible for bend ing and twisting, are balanced out by the elastic forces of the cantilever. These latter are mod elled by equivalent springs with 'normal' and 'lateral' stiffness.

It should be noted that the lateral forces can be $\dot{\sigma}$ etermined not only by friction, but also by the local slope of the surface [3, 32]. Best es, there always exists some relation between the normal force and the lateral force, especially in the case when the latter is $\dot{\sigma}$ irected along the axis aligned with the long side of a cantilever.

One further reason can be that the probe is positions at a small angle α to the horizontal to ensure contact with the surface rather than the plane size of the cantilever. Since the probe has a height of the ord er of several microns, the microroughness of such a scale may catch on the cantilever [33]. As a result of this slope of the probe, its normal and lateral isplacements are related by the following equation: $\Delta z = \Delta x \cot \alpha$.

Quantitative analysis of the lateral and normal forces in the AFM requires knowled ge of the normal and lateral stiffness of the cantilever, on the one hand, and the geometry of the probe, on the other. Calculation formulas for the stiffness with regard to d ifferent geometries of cantilevers can be found, for example, in Ref. [34]. Recently, a d irect method for d etermination of the lateral stiffness *in situ* was proposed. For a cantilever in the form of a rectangular parallelepiped, the normal and lateral elastic stiffness are [35]

$$k_{\rm n} = \frac{Ebt^3}{4a^3} \,, \tag{2.1}$$

$$k_l = \frac{Gbt^3}{3aH^2},\tag{2.2}$$

where E and G are Young's modulus and the shear modulus, respectively, b and t are the linear \dot{d} imensions of the cross section of the cantilever, a is the length of the cantilever measured from the point of its clamping to the point of attachment of the probe, H is the length of the probe (tip) of



Figure 1. (a) Scheme of an AFM with optical detection of the cantilever à isplacement. The sample is mover by a piezomotor having three egrees of free $\dot{\mathbf{r}}$ om (X, Y, Z). The $\dot{\mathbf{r}}$ is placements corresponding to the surface topography are uset for the formation of an image. (b) Force curve of the lowering/lift of a probe to/from a surface shows their epenir ence of the force applied to a contact (vertical bend ing of the cantilever) on the d istance between the cantilever and sample: on portion A of the curve there are no probe-surface forces, since the probe is far from the surface; B — a stable attractive regime und er the action of the Vand er-Waals forces; C — the grat ient of the attractive force excect s the normal stiffness of the cantilever, therefore the probe loses stability and sudd enly 'sticks' to the surface; D – further $\dot{\mathbf{q}}$ ecreasing the $\dot{\mathbf{q}}$ istance between the probe and the sample; E — the movement of the cantilever is reversed in ord er to avord probed isruption; at hesion between the probe and the surface hold s the contact und er the action of a stretching force; F—the stretching force excest s the critical force of etachment, and the probe 'falls off' the surface.

the AFM measured from the neutral (long) axis of the console to the apex point of the probe. For commercial silicon cantilevers, typical values of constants (2.1) and (2.2) are of the ord er of 1 and 100 m⁻¹, respectively.

Another practically important formula d etermines the fund amental resonance frequency for the vertical oscillation of a cantilever:

$$\Omega_0 = \frac{1.95b}{a^2} \sqrt{\frac{E}{3\rho}},\tag{2.3}$$

where ρ is the $\hat{\mathbf{d}}$ ensity of the console material. The resonance frequency of lateral oscillation (corresponding to bending $\hat{\mathbf{d}}$ eformations) is obtained by multiplying expression (2.3) by b/t. Using formulas (2.1)–(2.3), one candie fine an 'effective' mass of an equivalent oscillator by the formula $k = m_{\text{eff}}\Omega_0^2$. Generally, with allowance for the linkage of the probe with the surface, the $\dot{\sigma}$ etermination of the resonance frequency is a rather complicated task, and the point-mass approximation used to $\dot{\sigma}$ escribe the oscillatory motion $\dot{\sigma}$ ynamics may result in a considerable error. Despite this fact, the simple harmonic model is widely used for the $\dot{\sigma}$ escription of the model ulation model of the AFM.

2.1 Normal force measurement mode

Figure 1b shows schematically the 'force-d' isplacement' curve reflecting the d eperd ence of the vertical berd ing of a cantilever and the force applied to a contact on the vertical $\dot{\mathbf{d}}$ istance between the sample and the remote (not $\dot{\mathbf{d}}$ eform $\dot{\mathbf{d}}$) part of the cantilever [3]. Thed ifferent portions of this curve correspond to the following situations: A — the absence of any interaction force; B — the first stage of attraction to the surface; C — the 'sticking' of the probe to the surface occurring at the instant when the gradient of an attractive force acting from the surface exceet s the normal stiffness of the cantilever; D — the contact (repulsive) \mathbf{mot} e; since the probe operates in the more of repulsive interaction with the surface, the cantilever is concave toward s the surface, and the force load ing the contact is positive and correspond s to the external force; E — the movement of the console is reverse in of er to avor probed isruption; owing to a hesive forces, contact is not lost when the applied force changes its sign and becomes negative; now the cantilever is concave upward; F a negative force applied to the cantilever and tending to $\dot{\mathbf{d}}$ etach the probe from the surface exceed s the critical force of at hesive sticking, and the probe 'falls off' the surface.

Figure 1b allows one to $\dot{\sigma}$ istinguish two main motes of interaction of the probe with the sample: the attractive mote $\dot{\sigma}$ etermined by Vand er-Waals, capillary, electrostatic, magnetic forces) and the contact mode corresponding to repulsive forces. Such a classification, however, is not exactly correct, sinced ifferent parts of the probe can simultaneously und ergo the action of repulsive and attractive forces from surface atoms. Therefore, it is more pertinent to speak of ad ominant type of interaction for the probe as a whole.

In the first experiments the AFM was user for measuring the surface topography. In such experiments a feer back loop was user to maintain the vertical d isplacement of the cantilever or the normal force at a constant value when scanning along the surface. The corresponding 'constantheight' and 'constant normal force' modes allow one to obtain atomic resolution both in the repulsive and attractive modes. Figure 2 illustrates the indicated modes as well as socalled 'error-signal' and 'mod ulation' modes.

In the constant-height $m\sigma \hat{e}$, the feet back loop maintains the $\hat{\sigma}$ istance between the apex of the probe and the surface at a constant value. The feet back signal is calibrated as the probe height above the surface. However, the rest ual (not compensated) $\hat{\sigma}$ isplacement of the cantilever exists, since otherwise the feet back loop $\hat{\sigma}$ oes not operate. This signal is used in the error-signal mod e.

In the case of mechanical contact of the probe with the surface the contact area incluit es many atoms, therefore the contact $m\sigma t$ e of the AFM d t oes not generally provide atomic resolution of a surface.

2.2 Lateral force measurement mode

The lateral twisting of a cantilever can be $\dot{\sigma}$ etect $\dot{\sigma}$ simultaneously with the surface topography. The peculiarities of a surface profile which are not resolved in other modes can be



Figure 2. Basic operating mot es of AFMs. The arrows show the movement of the cantilever and the sample. (a) In the constant-height mot e, the sample moves horizontally and the d isplacements of the cantilever are monitors i. The synchronous (with scanning) recost ing of the height is the topographic (force) image of a surface. (b) In the constant-force more e, a feet back loop prevents larged isplacements of the probed own to and up from the surface. The variations of thed isplacements of the cantilever are minimizer owing to the at justment of coort inate z by the feet back loop so that the d eformation of the cantilever remains constant. The feet back signal is calibrater as the probe height above the surface. (c) In the errorsignal mot e, the rest ual (not compensated by the feet back loop) movement of the cantilever is use . (¢) In the mot ulation mot e, the cantilever oscillates in the vertical irection un er the action of a perior ic force. The amplitude of oscillation is monitored synchronously with the displacement of the probe in the (x, y) plane. One can also monitor the variations of frequency or phase of cantilever vibration. By analogy with the normalcontrast mot e, one can use the lateral-contrast mot e. In the latter case the moi ulation moi e is also possible.

visualizer owing to the distinctions of friction characteristics of the surface.

Surface images in the lateral force $m\sigma$ e reflect the stickslip (SS) effect exhibiting a perior icity of the lattice constant correspond ing to a given sample [39, 40]. An und erstand ing of the physics of this effect still remains unsatisfactory, since the contact area generally involves a large number of atoms (10– 10000). It is unclear how such a large group of atoms transfers over the interatomic istance as a whole. When measuring the lateral forces on alkaline-halod crystals, a perior icity correspond ing to one-half the lattice constant is also observed [3, 39].

In these experiments such an important characteristic as the 'friction force-load ing force' d epend ence is measured [35, 41-43]. It is obtained by subtraction of the average values of a lateral force applied to the cantilever in the process of scanning the surface in the direct and reverse directions. The normal force is maintained constant, and thed ifference of the average values of the lateral force is taken with a factor of 1/2. A 'friction loop' obtained in the process of the probe movement is shown in Fig. 3 [43]. Period ical spikes of the lateral force are related to the SS effect. After passing one loop, the value of the normal force changes and the process repeats. Thus, a series of the average values of friction forces is d etermined corresponding to given load s. One d is ad vantage of this methor is that with ecreasing the load the probe is force out of contact pre ominantly in the regions of lesser at hesion, therefore the portions of the surface with higher at hesion to not exhibit friction at the least applied load s.



Figure 3. 'Friction loop' of lateral forces correspond ing to the stick-slip mot e measured by scanning a silicon nitrid e probe over the KF(001) surface in vacuum. The arrows point in the $\dot{\sigma}$ irection of scanning. Hysteresis suggests the presence of energy $\dot{\sigma}$ issipation. The average and maximum values of lateral forces for each scanning $\dot{\sigma}$ irection are ind icated. (Reprod uced with the permission of Salmeron [39], copyright of the American Physical Society, 1998.)

We will revert to the etaile theoretical analysis of Fig. 3 in Section 3.1. At this point, we call attention to such interesting d etails as a shift of the positions of the maxima and minima of the lateral force at the direct and reverse movement of the probe as well as the fine structure of period ical spikes of the lateral force. The amplitude of variations corresponding to the fine structure is (in the case of Fig. 3) about 0.1 nN. This gives an estimation of the value of the lateral force contrast achiever in experiment. If the lateral stiffness of a tribocontact has a value of the of \mathbf{t} er of 1 N m^{-1} , the equivalent spatial resolution is about 0.1 nm. Lateral resolution of the same of er is typical for all basic mot es of AFMs and STMs, whereas for the normal contrast the value of spatial resolution is one or two of ers higher. Therefore, at the same value of the normal stiffness it is possible to measure normal forces of about 1 pN (see Section 3.2).

2.3 Modulation mode

The general $\dot{\mu}$ ea consists in the application of an oscillating force to the probe setting it into force $\dot{\mu}$ vibration along the normal to the surface of a sample. Further record ing the

ampliture e of oscillation is performed synchronously with the d isplacement of the probe in the horizontal plane. If a feed back loop maintains this ampliture e constant, the probe 'feels' the surface (Fig. 2i). In this case one cand etermine the relief of a surface with atomic resolution analogous to resolution which can be obtained with the use of the normal more.

If the probe and sample are right, the displacement of the latter along the normal causes mainly an elastic response of the cantilever, but if a surface is soft, it und ergoes an add itional compression and the response of the cantilever is decreased. Therefore, in the process of scanning at a constant height, the variations of the amplitud e of probe vibration reflect local variations of the contrast of the elastic properties of the surface. Among the mod ifications of this method are the tapping mod e [36], the extend disconstruction of the and the measurement of 'force – normal displacement' diepend ences at each point of a scan line (force surface cartography [44]). The latter mod e is similar to the method used in nanoind entors, and it is considered in distance to the following section. Other versions of the mod ulation mod e are described, for example, in paper [45].

If a cantilever is to be sensitive to the elastic properties of a sample, its stiffness must be comparable with that of the surface, since taken together they are similar to a pair of springs joiner in tan em (Fig. 4a). Therefore, if one of the springs has smaller stiffness, it takes upon itself the main d eformation. This constrains the sphere of application of this method to the case of relatively soft surfaces (polymers and biological tissues) if low-stiffness cantilevers are used. On the whole, this method visualizes the relative d istribution of the elastic properties of the sample, since the actual area of the contact remains und eterminer. The d etermination of the absolute values of local elastic mod uli becomes possible, if the contact-mechanics approximations are used in add ition for the estimation of the area of the contact.



Figure 4. Normal and lateral stiffness in the AFM. The cantilever and surface und ergo normal (a) and lateral (b) compression with the resulting d isplacements Δz and Δx , respectively. In both cases the cantilever and surface taken together are similar to a pair of springs joined in tand em. If one of the springs has smaller stiffness, it takes upon itself the main d eformation. Since in experiments the totald isplacement of a cantilever is measured, its stiffness must be comparable with the stiffness of the contact in ord er that the cantilever be sensitive to the elastic properties of the sample. (Reprod uced with the permission of Salmeron [39], copyright of the American Physical Society, 1998.)

2.4 Normal stiffness measurement and nanoindentors

The $\hat{\mathbf{d}}$ etermination of the normal stiffness of an elastic contact is base $\hat{\mathbf{d}}$ on the relationships of contact mechanics relating the value of an applie $\hat{\mathbf{d}}$ normal force P with the $\hat{\mathbf{d}}$ eformation of the sample surface x and $\hat{\mathbf{d}}$ with the rad ius of the contact area a. The normal contact stiffness and the microhad ness of a surface are $\hat{\mathbf{d}}$ efine $\hat{\mathbf{d}}$ as $k_c = \hat{\mathbf{d}} P/\hat{\mathbf{d}} x$ and $H = P_{\text{max}}/\pi a^2$, respectively, where P_{max} is the maximum load ing force producing an impression in a sample with area πa^2 (after removing the load). These relationships form the basis of the surface ind entation (microd eformation) method [46].

The original evelopment of the ind entation method s was connected with studies of the mechanical properties of materials and was not directly related to problems of nanotribology. However, progress in the d evelopment of the AFM technique has let to the 'intersection' of the corresponting methods, since an AFM probe is essentially a nanoir entor. To obtain the loading force characteristics of a contact, all one needs to do is to control the value of the normal force. The high resolution achiever with the use of the AFM allows one to investigate microhant ness and many other characteristics of film coatings and microparticles with an accuracy and resolution much superior to the accuracy of stand and microind entors. Nevertheless, the commercial systems of ind entation on the basis of the three-cornered à iamonà Berkovitch inà entors have now beenà evelopeà to a high d egree of perfection [46], and some of them provid e normal force and d eformation resolution not worse than 10 nN and 0.1 nm, respectively.

By applying an $d\hat{r}d\hat{r}$ itional oscillating load to an independent one can conduct continuous measurement of the contact stiffness through monitoring the amplitud es of d isplacement oscillation caused by the corresponding force or through the d etection of phase shifts between force and d isplacement oscillation. In such a manner one can also measure the viscoelastic characteristics of a contact [46].

2.5 Lateral stiffness and friction force

In a similar manner one can cod^{3} uct the measurement of the lateral stiffness of a contact (Fig. 4b). For commercial AFM, this mode was first implemented in works [35, 47, 48]. The d erivative of the lateral force with respect to the lateral coord inate corresponds to an equivalent stiffness of the cantilever-surface system:

$$k_{\rm e} = \frac{\dot{\mathbf{d}} F}{\dot{\mathbf{d}} x} = \frac{k_{\rm l} k_{\rm c}}{k_{\rm l} + k_{\rm c}} ,$$

where $k_1 \operatorname{ant} k_c$ are the lateral stiffnesses of the cantilever and the contact, respectively. The authors of work [47] also introd uce an add itional stiffness d etermined by the elasticity of the probing tip. The resulting torsion response of the cantilever ΔF to an oscillating lateral d isplacement Δx is measured with the use of a synchronous d etector.

With a knowledge of $k_{\rm l}$, one can obviously find the contact stiffness $k_{\rm c}$ and then the area of the contact πa^2 using the contact-mechanics formula

$$k_{\rm c} = 8a \left(\frac{2-\eta_1}{G_1} + \frac{2-\eta_2}{G_2}\right)^{-1}, \qquad (2.4)$$

where $G_{1,2}$ are the shear mot uli of the probe and the sample, $\eta_{1,2}$ are the Poisson coefficients. Since typical cantilevers user in AFMs have relatively high lateral stiffnesses, the contact lateral stiffnesses can be measured for a broad spectrum of soft and had materials [3].

In accord ance with the theory d eveloped by Bowd en and Tabor [12], in the case of a d ry' contact the friction force for an ind ind und microcontact is d etermined by the following formula:

$$F = A_1 \sigma_0 + \pi a^2 \tau \,, \tag{2.5}$$

where A_1 is the cross sectional area of a cut occurring in the process of 'ploughing' of a sample by a probe, σ_0 is the limit of yield of the surface material at lateral compression, πa^2 is the actual area of the contact, and τ is the shearing stress. In the macroscopic case, there exist an interrelation between the shear mod ulus and the shearing stress: $G \approx 29\tau$

Byc efinition resulting from Amonton's law, the classical friction coefficient is equal to

$$\mu = \frac{F}{P} \,, \tag{2.6}$$

where *P* is the normal load ing force. Taking into account expressions (2.5) and (2.6), the friction coefficient can be presented in the form of a sum of two components, one of which is related to abrasive friction and the other one is related to ad hesive friction: $\mu = \mu_A + \mu_{AD}$. For nanotribology, of the greatest interest are the ad hesion components of the force and the friction coefficient which, as is shown in Fig. 3, allow one to 'visualize' the atomic structure of a surface. As follows from experiments carried out with the use of AFMs, formula (2.5) can be used in this case only for the determination of the average values of the friction force in the contact of a probe with a surface. Nevertheless, it hold is its valid ity for the interpretation of experimental at in the case of elastic contacts and allows one to relate the macro- and microscopic characteristics of a surface.

2.6 Force calibration and determination of the probe shape

The geometry of the contact area is in efinite if the shape and d imensions of the probe use are unknown. It is also very d ifficult tod etermine the chemical composition of a probe in the vicinity of its apex. The indicated factors, however, are $\dot{\mathbf{d}}$ ecisive, since we are trying to understand the properties of a sample that is one of two parts of the contact interface area. To obtain a surface image, commercial cantilevers with a ratius of curvature (in the lower part of the probe) of the of \mathbf{r} of 10-50 nm are use in AFMs. In this case the atomicscale resolution is d etermined by a small group of probe atoms (or at sorbet foreign particles) near its apex. Obviously it is very d ifficult to control this group of atoms in the process of experiment. The resolution of topographical details of a large scale is obtained as the result of convolution of the geometrical shape of the probe and a portion of the surface relief and is not always unambiguous either.

Usually, the AFM probes (tips) are characterized by the so-called aspect ratio — the ratio of their length to the rad ius of curvature in the lower part. The length is measured from the point where the probed iameter is equal to the quad ruple rad ius of curvature near the apex. In the case when the aspect ratio of a reliefd etail is higher than that of a probe, artifacts arise resulting from the fact that the probe represents its own portrayal, since in the process of the scanning of a rd ge of a surface it can only 'feel' the top part of the rd ge.

If test-relief features are known or a force calibration has been performed, it is possible to $\dot{\sigma}$ etermine the probe shape

in situ on a nanometer or micrometer scale [42, 49]. The *ex situ* calibration of the probe shape using transmission electron microscopy also has a wit e application [35]. The authors of work [50] proposet a methor ford etermination of the probe shape using the measurement of the backward scattering yiel for a low-intensity ion beam. This can be performed in the work chamber that contains the sample.

In the process of measurements of the probe geometry, $\dot{\mathbf{\sigma}}$ ouble and some other und estrable structures were revealed. Their study is crucial for obtaining AFM images, accurate measurements of forces as well as nanotribological experiments.

In connection with these problems, new possibilities were opened up owing to application of fullerenes and isolated nanowires as probing elements of AFMs. These objects have welled efined structures and high strength. So, the authors of work [51] were able to fix a single molecule of C_{60} onto the tip of an AFM, and in work [52] this was d one with a nanowire. The possibility of obtaining atomic resolution with such structures was theoretically substantiated in work [53].

In contrast to right silicon (or silicon nitrit e) probes, nanowires $\dot{\mathbf{d}}$ o not fail when they make contact with a surface and restore their form after removing the load. A very important at vantage of the 'nanowire-surface' contacts is the constancy of the area of the contact zone tirectly related to the value of the friction force. In this case we have a good chance of studying the mechanism of at hesive friction in more $\dot{\mathbf{d}}$ teal, since the area of the contact can be controlled.

For experimental nanotribology, a number of other factors are of importance. Among these are the nonlinear properties of piezoceramics, hysteresis, material creep, thermal $\dot{\sigma}$ rift and so on. An extend $\dot{\sigma}$ iscussion of these questions can be found in paper [32] (see also references in Ref. [3]).

2.7 Other experimental methods

Surface force apparatus (SFA). The construction of this apparatus wasd eveloped by Israelachvili's group [4, 20, 26]. The d evice consists of two atomically-smooth plates (usually mat e from mica), attachet to the base surface of cylint ers being brought into close contact. The surfaces of the plates can be treated and /or coated by a layer of material und er stud y in a liquid or sold state as well as can be immersed in a liqué metium und er well controlled conditions. Force ở rivers connected to cylind er hold ers provide controlled normal and lateral forces to be applied to the plates as well as the maintenance of a gap between the plates with an atomic accuracy. The area of the contact and the distance are measure by optical or capacitance methods. Interatomic forces acting between the surfaces, which interact via an interlayer, can be attractive, repulsive, oscillating or can have a more complex form [4, 26].

A weakness of this methor is that the lateral resolution is limiter. A typical value is several micrometers. Provering vacuum conditions is also a problem. Moreover, to obtain meaningful quantitative results, in $\vec{\sigma}$ ecciling on a particular material for the plates, one restricts oneself mainly to mica.

The SFA allows one to study the molecular properties of liquidy s and so it is especially useful for investigation of the compression properties of liquidy lubricating materials. Such experiments are of great importance for the elucidy ation of the nature of the lateral slip. With the use of this methody, the effect of exfoliation of liquidy separating the plates was foundy when changing the d istance between the plates by a value of

an atom $\dot{\mathbf{a}}$ iameter [54]. In this case, perior ical attractive and repulsive forces correlating with the layer $\dot{\mathbf{a}}$ (atomic) structure of the liquid interlayer were $\dot{\mathbf{a}}$ etected. This effect was also observed with the use of an AFM for the contacts of a silicon probe with the mica (graphite) surface $\dot{\mathbf{a}}$ of ecanol was used as a liquid interlayer) [55]. Experiments carried out with the use of the SFA reveal a variety of ynamical properties and phase transitions ind uced by the shear of ering of a film structure separating the plates. We will return to a more $\dot{\mathbf{c}}$ etailed $\dot{\mathbf{c}}$ iscussion of these effects in Section 3.4.

Quartz crystal microbalance (QCM) method. This methor was first use to control the growth of submonolayer films. It is realized through the measurement of a resonance frequency shift for a quartz oscillator whose resonance frequency d epend s on the mass of a film at sorbet on a plate. Such experiments were usually carrier out to control the growth of metallic films. However, as was elucid ated later, an interesting feature occurs in relation to inert gas (argon, krypton) films at sorbet on these metallic films and weakly bound with their surface. In this case the O-factor shift for a quartz oscillator in uce by the existence of friction forces between an at sorbet film and a substrate was observed [21]. This allower one to estimate the characteristice ecay time of the at sorbet film motion relative to the substrate. If the corresponding friction force acting on the at sorbate atom is proportional to the slip velocity and equal to $F = -\alpha V$, then the slip time is equal to M/α , where M is the mass of the atom. As follows from experiments, the slip time is several nanosecond s. This allows one to estimate the characteristic value of the friction force. For krypton atoms, it is about 10^{-16} nN.

Using this methor, the phase transformations of a^{\dagger} sorber films resulting in the shifts of the resonance frequency an^{\dagger} Qfactor of a quartz oscillator because of the transition of a film from a liquid state to a sold one were found as well [23]. The theoretical interpretation of this effect is based on the assumption that the had ener film forms an incommensurate structure with a substrate and therefore slips much further (with less friction).

In conclusion of this section, it should be noted that even the above briefd iscussion of experimental techniques used in present d ay nanotribological investigations d emonstrates a surprising variety of physical phenomena occurring on the nanostructural level. As ever enced by the foregoing, progress in their stud y is possible with the use of different method s that complement each other. Common to all these method s is the real possibility to measure ultra-small forces and d istances visualizing the d iscreteness of atomic structures and interatomic interactions.

3. Physical processes in nanotribocontacts

When d iscussing physical processes in nanotribocontacts, we attempt not only to embrace d ifferent phenomena observed experimentally, but also, where possible, to include their theoretical interpretation. An extended consideration of some of the existing theoretical models is given in Section 4.

3.1 Stick – slip effect

The stick – slip effect is crucial for the contact \mathbf{mot} e of AFMs. On the atomic level, this effect was first observer in work [2] when measuring lateral forces which act on a tungsten probe slipping over the surface of high-orienter pyrolitic graphite. Similar measurements were later cond ucted in many works (see, for example, Refs [56–58]) with a broad spectrum of contacting materials ranging from soft materials (silicon nitrid e probe — stearine act) to had ones (diamond – diamond) (see references in paper [3]). The surfaces of alkaline-halod crystals (NaF, NaCl, KF, KCl, KBr) were also studied [39].

Fujisawa et al. [59] carrier out a comparative investigation of the SS effect for the $\dot{\sigma}$ ifferent combinations of probe and sample materials. The perior icity of the probe slip over a surface observer in these experiments correspond of the atomic-relief topography of the surface in the normal AFM mor e, but the positions of the maxima and minima of lateral and normal forces were slightly shifter relative to each other.

No experiments are presently available in which lateral resolution would be observed without the SS effect, however, a frequently observed lateral contrast is even higher than the correspond ing normal contrast. Because of this the authors of works [33, 73] believe that the period icity of lateral interaction is responsible for the overall contrast observed including normal-mode topographic images.

The SS effect was also observer in experiments using a surface force apparatus [60], but a transition to a continuous slip without wear was noter at much higher velocities. Thus, to compare this $\dot{\sigma}$ at a with the AFM $\dot{\sigma}$ ata, it is necessary to increase the scan velocity of AFMs.

Does this period icity of the SS effect signify that the probe atoms form a structure commensurable with the atomic structure of a sample? Even for probes with a $\dot{\sigma}$ isog ere atomic structure, the period icity of lateral forces corresponds to the translational symmetry of the sample. In typical experimental situations, both lateral and longitud inald eformations of a cantilever generally take place, but the latter may also be d etermined by the change of the normal force. Therefore, there always exist a relation between the correspond ing signals in the lateral and normal mod es. If this relation is not controlled, it can totally d istort the results of measurements.

Tomlinson [61] was the first to raise the question of the role of atomic structure in the relative movement of contacting surfaces. Since that time many authors have attempter to explain the SS effect using more ernizer classical notions of Tomlinson and the molecular d ynamics method (see references in papers [3, 4] and Section 5). In the present a ymore els d eveloping these d eas, a probe is considered as a point particle with a point mass without any internal d egrees of freed om [56, 57], or allowance is made for its multi-atomic structure [62, 63]. A simplified, but visual picture of the SS effect is as follows.

Initially the probe is at a point of the minimum of the potential energy of the 'probe-surface' system. The interaction between the probe and the surface isd efined by a period ic potential reflecting the translational symmetry of the atomic structure of the surface. Essential to the mod el is the assumption that ad iabatic cond itions are fulfilled at each step of probe movement. The lateral load ing of the contact caused by cantilever scanning results in storing energy in the form of the elastic energy of the contact, the cantilever and the sample (see Fig. 4b and Fig. 13). The relative movement of the probe and the surface begins at the instant when the stored energy is sufficiently large that the probe can 'jump out' of a potential gap and fix itself at another point of the surface. Then the system relaxes, and excess energy raph lyd issipates from the contact area via the electron – phonon subsystem.

The $\vec{\sigma}$ issipation time is very small, since the characteristic velocities of electrons and photons are many orders of magnitude e higher than the typical velocities of AFM probe scanning $(10^{-7}-10^{-4} \text{ m s}^{-1})$.

As follows from experiments and model calculations, in order that instability related to the SS effect be observed, it is necessary to use the combination of a 'soft' cantilever and a 'stiff' surface strongly interacting with each other. In this case, the softer the contact, the more energy d issipates. However, in the models the possible mechanisms of energy d issipation in which the friction force is proportional to the velocity are not taken into account. Slip without friction was theoretically substantiated in works [62, 64] when the above conditions were not fulfilled.

The oscillator mot el at equately d escribes the SS effects only und er the condition of critical amping of a cantilever. This is its weak point when the large elasticity of cantilevers is taken into account. To eliminate this contradiction, Johnson and Wood house [65] introduced the contact stiffness and found a relationship between the effective stiffness of the 'cantilever-surface' system and the amplitud e of the periodic friction force (for more d etails, see Section 5.2).

On the whole, the weakest point of this theory is inconsistency between the point oscillator mot el ant the actual situation with the AFM probe when the contact area measures tens of nanometers and hence involves many atoms. In this case, as follows from calculations [66], at d ifferent positions of the apex of a d iamond probe on the graphite surface (for a real-size probe with a ratio is of curvature of 5 – 15 nm) the change of the potential energy of the system after relaxation d oes not exced 0.2 eV. Therefore, one cannot say that the probe jumps from one position of energy minimum to another. Experimental evid ence lies in the fact that the period of the SS effect coincides with the period of a surface atomic structure. Thus, in the contact lateral mot e of an AFM we must not speak of 'true atomic surface resolution', as in the mot ulation mot e [38], but about 'atomic contrast'. This is supported by the fact that the point atomd efects of surfaces are not resolver in the contact more.

A more realistic geometry of the 'equilibrium' contact area correspond's to Fig. 4a, and any sharp lateral twisting of the cantilever (Fig. 4b) is connected with increasing energy. To put it otherwise, each position of the probe on the surface correspond's to the minimum of energy.

The molecular d ynamics calculations also predict the presence of the SS effect [67–69]. Land man et al. (see Ref. [67] and references therein) and Sorensen et al. [68] studied Si (probe)-Si (surface) and Cu (probe)-Cu(111) (surface) contacts, respectively. Friction without wear was observed at small load s. Ad ecrease of the friction force with increasing scan velocity was also noted. These results will bed iscussed more comprehensively in Section 4.3. Here we only point out that the most serious objection to the results of the MD calculations connected with the interpretation of the SS effect is that the range of velocities user in these calculations incluit es velocities $(1-2000 \text{ m s}^{-1})$ consider that the scan velocities in AFM. Another problem, also relating to quasi-static motels, is the lack of information about the actual structure of the probe and the lack of control over it. Nevertheless, the numerical MD experiments have enriched our und erstanding of structural changes taking place in the contact area.

In my opinion, a clear-cutd istinction ned s to bed rawn between conservative lateral forces acting on the probe and d issipative forces (see Section 4.4). When consd ering the probe movement correspond ing to the friction loop shown in Fig. 3, we are d ealing with the maxima of a static force d etermining the onset of slip. However, we have no knowled ge of the atomic structure of the contact area at the correspond ing moment and cannot answer the question of whether there is any motion of atoms within it. The authors of work [35] believe, for example, that at the periphery of the contact restricted slip of atoms takes place even at very small lateral forces. Hence, the lateral force observed cannot be totally assigned either to a d issipative force or to a conservative one. It is possible that it is a combination of both components.

As was mentioned in Section 2.5, experimental information obtained with the use of an AFM for lateral forces (Fig. 3) is still not finally und erstood. This concerns, for example, the interpretation of the fine structure of friction loops. The d iscreteness of the small variations of the lateral force observed in experiments most likely reflects the iscreteness of breaking ind ivid ual ad hesive bond s that is analogous to breaking the bond in the vertical irection in the lowering-lift mod e of the probe [70].

As to the shift of the lateral contrast on reversing the ở irection of probe movement (Fig. 3), there is nothing out of of inary in it, since the contrast does not irectly isplay an atomic structure. For a probe in the extreme right position (the upper curve in Fig. 3) the system is read y to make a microslip, therefore itd oes not matter whether the probe will continue to move to the right or reverse its d irection — in either case the force magnitude must further decrease (that is actually observed). As a result, after a sharp d ecrease of the lateral force in the initial stage of the reverse movement of the probe this force turns out to be close to zero, the contact gets 'unload d' and only then a new increase of the lateral force begins, the force continuing to increase until the next slip cycle begins. This shows once again that sharp changes of the lateral force are irreversible and connected with the dissipative character of the slip process.

The atomic period icity of the SS effect is qualitatively explained by the model of making and breaking ad hesive bond s (see Section 4.4). At each position of the probe on the surface, the 'spot' of contact covers a particular area of the surface, and for a spot of a specified form the number of surface atoms beneath it varies d epending on the lateral cooft inates with the surface lattice period. This was demonstrate, for example, for one- and multilayer nanowires in last year's work by the author of this review [53]. If the probe is located at the point corresponding to the minimum number of at hesive board s in the vicinity of the contact spot bound ary, then for an abrupt microslip (over a small d istance in comparison with the surface lattice period) the d issipative friction force will be minimal, since the number of broken and newly-made ad hesive bond s is moderate, and smalld iscrete jumps observer as a fine structure of the lateral force (see Fig. 3) are not accompanied by the loss of stability of the system, which continues to accumulate energy. On the contrary, in the position corresponding to the maximum number of bont s along the spot bound ary, the breaking of these bond s because of the microslip with a subsequent sharp d ecrease of the lateral force at the cantilever becomes catastrophic in character — and the probe gets away. Of at hesive bond s (behind) are broken, red ucing resistance to the onward movement of the probe, and new bord s, made ahead, d raw it forward. The character of this movement is

at equately represented by a mot el in which atoms-magnets are stacked on the surface in the form of a regular grit and have a vertical gree of freet om, and a probe having a flat form (with the same magnets on its surface) is fitted to a pend ulum whose axis moves with a constant horizontal velocity. This mot el allows one to visualize the atomic SS effect on the macroscopic level.

On the whole, many fund amental aspects of the SS effect still remain to be seen. First and foremost there is no clarity in d etermination of concrete experimental conditions und er which the SS effect must be observed, in concreted efinition of the mechanisms of issipative losses, in the problem of the period icity length and so on. The latter is especially urgent for alkaline-halod crystals, for which slips both over the lattice period and over one-half the lattice period were observed.

3.2 Adhesion effects

At hesion effects are obviously essential to the problem of atomic friction, since they $\dot{\mathbf{d}}$ etermine the area of the contact and the interaction of the probe with the sample [6]. At hesive forces can be $\dot{\mathbf{d}}$ irectly measured with the help of an AFM using the lowering-lift mode or the measurement of the 'friction force – load ing force' $\dot{\mathbf{d}}$ eperd ences [35, 42, 43, 72]. In the event that contact mechanics are used for $\dot{\mathbf{d}}$ at interpretation, two main parameters being $\dot{\mathbf{d}}$ etermined in these measurements are the shearing stress and the $\dot{\mathbf{a}}$ hesion work. The shearing stress is $\dot{\mathbf{d}}$ irectly proportional to the critical lateral force causing probe slip in the stick-slip mode. The $\dot{\mathbf{a}}$ hesion work is equal to the specific energy (per unit area of a contact) required to break the contact. By $\dot{\mathbf{d}}$ efinition, the $\dot{\mathbf{a}}$ hesion work is

$$\gamma = \gamma_1 + \gamma_2 - \gamma_{12} \,, \tag{3.1}$$

where γ_1 , γ_2 , γ_{12} are the specific surface energies of the probe and the sample and the interface energy of the contact, respectively.

The basic problems to be solved are concerned with the $\dot{\mathbf{q}}$ epend ence of these quantities on the atomic structure of the contact, temperature, external pressure, chemical composition and so on. Ad istinction ned s to bed rawn between d ry' vacuum conditions and the more complicated case of a 'wet' surface when intermolecular forces may considerably vary owing to the presence of molecules of a solvent or ad issolved substance.

In the case of $\dot{\alpha}$ ry' friction, the a^{\dagger} hesion work is $\dot{\alpha}$ etermined by the force of $\dot{\alpha}$ etachment of an AFM probe from a surface. The force of $\dot{\alpha}$ etachment is negative in sign and correspond s to a force applied to a cantilever which is necessary for surface separation. For elastic a^{\dagger} hesive contacts in the case of a parabolic-profile probe with a rad ius of curvature *R*, the Johnson-Kend all-Roberts (JKR) theory [73] (for more $\dot{\alpha}$ etails, see Section 4.1) gives the following expression for this force:

$$P_0 = -1.5\pi R\gamma \,. \tag{3.2}$$

The JKR theory $\dot{\sigma}$ escribes the elastic contact of soft materials with a strong short-range (attractive) $\dot{\alpha}$ hesive interaction. The contact of stiff materials with long-range attraction is best $\dot{\sigma}$ escribed by the Deryagin – Muller – Toporov (DMT) theory [27]. In this case the numerical factor in formula (3.2) is replaced by 2.

One further formula relates the remanent friction force F_0 at the point of probect etachment and the at hesion work. In

the JKR approximation they are related by the following formula:

$$F_0 = \pi \tau \left(\frac{9\pi R^2 \gamma}{8E'}\right)^{2/3},\tag{3.3}$$

where τ is the shearing stress, $E' = (1 - \eta_1)/E_1 + (1 - \eta_2)/E_2$, and $E_{1,2}$ are the moduli of elasticity of the components. In the DMT theory $F_0 = 0$, and the force of d etachment correspond s to the Vand er-Waals attractive force and in the case of a spherical probe is equal to

$$P_0 = \frac{HR}{6h^2} \,, \tag{3.4}$$

where *H* is Hamaker's constant, *R* is the rat ius of the probe, and *h* is the istance between the probe and the surface at the instant of attachment. Typical values of *h* and the *H* constant lie in the ranges 0.2 to 0.3 nm [73] and 0.6 to 2.5 eV, respectively.

Using formulas (3.2), (3.3) and the measured values of the P_0 and F_0 forces, the authors of work [40] found that $\tau \propto \gamma^{0.44}$ for the interaction of a platinum-coated probe with mica (und er high-vacuum condition). In this case a progressive d ecrease of these forces from one cycle to another was observed (Fig. 5). The authors believe that these peculiarities are connected with chemical or structural changes in the contact area ind uced by probe scanning. It is also assumed that these variations of friction and ad hesion may be d etermined by the change of the character of commensurability of contacting surface structures.



Figure 5. Progressive $\dot{\sigma}$ ecrease of the \dot{a} hesion energy and the shearing stress when measuring experimental 'friction force-loading force' $\dot{\sigma}$ epend ences in the case of scanning by a platinum-coated probe over a mica surface in vacuum. After each scan cycle the \dot{a} hesive force of $\dot{\sigma}$ etachment and the shearing stress are $\dot{\sigma}$ immished. This means that friction and \dot{a} the shearing stress are $\dot{\sigma}$ immished. This means that friction and \dot{a} thesion are sensitive to the changes of structure and /or chemical interactions in the contact area. Such behaviour takes place ind epend ently of the changes of the probe shape. (Reprod uced with the permission of Salmeron [43], copyright of the American Physical Society, 1998.)

The weak d epend ence of the shearing stress on the value of the d hesion work seems to be highly unusual, since more frequently a linear proportionality between these quantities is observed (in the absence of wear). The simplest mod el provid ing an explanation for this d epend ence is the 'cobblestone road' mod el equivalent to the Tomlinson mod el. The slip of surfaces in contact is considered by analogy with the movement of a carriage wheel. At rest the wheel land s in a hollow formed by cobble-stones, and to set it in motion, it is necessary to apply a lateral force large enough for the wheel to get out of this hollow. In this more el the role of attractive surface forces is player by the force of gravity. For an atomicsmooth surface, atoms correspond to the cobble-stones, but the picture considered will be the same for the contact structure shown in Fig. 4a. Experiments carrier out with the use of an SFA on surfaces covered by hyd roxyl groups and the molecular layers of liquid s support this model [4]. In these works it was also shown that for the systems of chain molecules the ad hesion work increases when the surfaces are brought into contact. Besides, hysteresis of the area of contact in the processes of bringing together and separating the surfaces is observed, and the friction force increases with increasing hysteresis.

Israelachvili proposet a theory [74] establishing a link between friction and at hesion which is determined by the internal structure of molecular structures (hyd rocarbons), but for d ry' tribocontacts, no at hesive and friction hysteresis shout be observed [43] in contrast with the pred ictions of this theory.

Another mot el establishing a link between the shearing stress and the at hesion work (in the case of d ry' contacts) was proposed in works [75] (for more d etails, see Section 4.4). Figure 6 shows the correlation d epend ence between the macroscopic values of the surface energy of metals and some other sold s and the prod uct of the shearing stress by the atomic rad ius plotted on the basis of the existing experimental d ata for homogeneous contacts [75]. As was mentioned in Section 2.4, the shear mod ulus isd irectly proportional to the shearing stress, therefore, it is believed that G and τ vary in concost, and Fig. 6 reflects equally the correlation of τ and γ . Fig. 6 shows that one can recognize two groups of materials with d ifferent coefficients of proportionality between τ and γ , or, alternatively, thisd epend ence is nonlinear. In the latter case it is nearly quad ratic: $\tau \propto \gamma^2$.

In the author's opinion particular emphasis should be placed upon the parad oxical results of comparative analysis of a correlation between the value of the ad hesion work measured with the use of an AFM and the expected macroscopic values of this quantity, on the one hand, and an analogous correlation for the values of the shearing stress, on the other hand. For example, for Si (probe)-NbSe₂ (sample) contacts experimental values of the shearing stress,



Figure 6. Correlation between the prot° uct of the macroscopic shear mot ulus by the atomic rat ius and the surface energy of sold s. The values of the surface energy are reduced to 0 K. (Extended version of a similar d iagram from Ref. [75].)

obtained with the help of the AFM at different radii of curvature of the probe, fall in the range 0.61 to 0.66 GPa, that is, are close to the value of τ in the macroscopic case, 0.57 GPa. At the same time the values of the at hesion work $(0.65-0.1 \text{ J m}^{-2})$ seem to be too small in comparison with its macroscopic values. For example, for hat silicon the surface energy is close to 1.8 J m⁻², for hat niobium it approximates 2.5 J m⁻². For selenium nod ata are available, however, it may be assumed that for hard NbSe2 its value ranges from 0.3 to 1 Jm^{-2} , since NbSe₂ has a layerer structure similar to that for graphite, and for graphite $\gamma \approx 0.33$ J m⁻². Thus, for the Si – NbSe₂ contact one would expect $\gamma_1 + \gamma_2 \approx 2.1 - 2.8$ J m⁻². Therefore, to obtain these extremely low values of the at hesion work observer, it must be assumed [according to formula (3.1)] that the phase interface energy γ_{12} is practically equal to $\gamma_1 + \gamma_2$. Such large values of γ_{12} are, in turn, indicative of a diramatic rearrangement of the atomic structure of the interface bound ary that, however, seems to be highly improbable in the case of the contacts of har materials. In particular, for the contact of homogeneous bot ies we have $\gamma_{12} = 0$.

Thus, the assumption that the or $\dot{\mathbf{r}}$ ers of magnitur es of the macroscopic characteristics of materials are retainer when going to a nanoscopic scale is not so apparent. An analogous conclusion follows from the analysis of the values of the ar hesion work in other experiments (see, for example, the $\dot{\mathbf{r}}$ ata of Table 1 in Ref. [3]).

Constit erably more complex at hesion effects are observed in the case of 'wet' tribocontacts. Many were stud is by way of measuring approach istance curves [4]. The use of the AFM method in this case appears to be particularly promising, since solvation forces are the least und erstod. Measurements of these forces on the surfaces of graphite and mica coated with nd of ecanol and octamethylcyclotetrazilocsane were cond ucted using an SFA [76]. The interpretation of solvation forces is easier when liquid is 'clamped' between two macroscopically-smooth plates, but not so apparent when one of theses plates is replaced by an AFM probe. The molecular d ynamics simulation of solvation forces for a 'nickel (probe) – gold' contact with a hexad ecane interlayer was performed in work [77].

The authors of work [78] stur iei the relation between ar hesion and friction for a silicon nitrid e probe on an Au(100) surface coater with chains of built-in organic molecules (alkanes). In these experiments a linear correlation between the macroscopic values of the surface energy determined from the contact angle of wetting, and friction forces was found.

Owing to the small area of the contact $\mathbf{ma^{i}}$ e between an AFM tip and a surface, it is possible to observe the 'quantization' of at hesive forces. In work [79] this effect was found when measuring at hesive forces between a silicon nitrit e probe and a glass surface coated with water. Discrete jumps of at hesive forces of the ord er of 1 pN were observed in the approach istance curves. The authors succeed et in revealing the thermomechanical fluctuations of the coord inates of the probe correspond ing to its different metastable positions. These fluctuations appear because of exfoliation of water and /or hyd rate ions on the surface of ionic crystals. In these experiments, the probability of localization of the probe at a d istance s from the surface is d etermined by the Boltzmannd istribution

$$p(s) \propto \exp\left[-\frac{V(s)}{k_{\rm B}T}\right],$$
 (3.5)

where V(s) is the potential energy, $k_{\rm B}$ and T are the Boltzmann constant and the temperature, respectively. The measured minima of V(s) obtained by way of inverting formula (3.5) have a period icity of 0.15-0.3 nm that is comparable with the immensions of water molecules.

A great number of other a^{\dagger} hesion effects follow from the MD simulation [4, 18, 69, 80–83]. Among these are the formation of a^{\dagger} hesive avalanches [84], the plastic creep of probe material with the formation of crowd ions and the generation of d islocations [82, 85], the vibration mechanism of compression and d isruption of metallic nanoparticles at inelastic impact [82] and so on. However, there are some contradictions between experiments and the results of the MD simulation. For example, in contrast with the MD calculations the hysteresis of a^{\dagger} hesive forces is not always found in experiments.

In connection with tribological problems, it should also be noted that in numerical MD experiments there is ever ence for the existence of ad ifferential strength effect (for mored etails, see Ref. [82]). The authors argue that the strength of materials for uniaxial compression is much higher than for stretching. If such an effect exists, the low strength of phase bound aries may be observed.

3.3 Chemical effects

Tribochemical effects on the macroscopic level were a^{\dagger} equately covered in monograph [86], however, the use of AFMs opens up new interesting possibilities [3, 6, 87].

Friction can both stimulate and suppress chemical processes, and these latter, in turn, affect friction that is sensitive to the chemical composition of the contact area. The chemical-composition dependence of normal and lateral forces may, in particular, be used to obtain the relevant images and to study the chemical reactivity of a surface.

Marti et al. [13] have shown that the measurements of lateral forces between a silicon nitrit e probe and a quartz surface place in a solution are dependent on the hydrogen ind ex of the solution. The authors attempted to relate the measured value of friction to the ad hesive hysteresis observed in experiments with the use of an SFA [60]. In accord ance with theory [74], in the case of 'wet' contacts, ad hesive and friction hysteresis is d ue to the influence of complex processes, such as the reorientation, interd iffusion and intertwining of the chain molecules of hydrocarbons. Ad hesive hysteresis takes place for d ry' contacts as well (see Fig. 5 and Ref. [43]), however, in this case the theory proposed in work [74] is not appropriate.

Friction hysteresis on the wet surfaces of alkaline-halo crystals was observer by Carpick et al. [39]. The measurer d epend ences of the friction force on the load ing force for the KCl and KBr surfaces are presented in Fig. 7. They d iffer ratically (in a qualitative sense) from analogous epert ences for elastic contacts (see Figs 5, 12, 13). To interpret these curves, the authors hypothesize that the contact area und ergoes a structural mot ification. Analogous (linear-type) d'epend ences were observer for golt, silicon nitrit e and organic films [88]. It is possible that such (linear) d epend ences are specific for tribochemical wear. In the case of a NaNO₃ wet surface in contact with a probe, the splitting of d iatomic steps into monoatomic ones and a material transport from steps to above-space terraces were note [89]. The influence of humd ity on the force interaction of a probe with a surface was also stud ied [16, 17].

Phenomena of tribochemical $\hat{\mathbf{d}}$ egraf ation were note in the cases of the MoS₂ surface as well as $\hat{\mathbf{d}}$ iamon $\hat{\mathbf{d}}$ -like film



Figure 7. Friction force $-\log^3 i$ ng force 'à epent ence for KCl (a) ant KBr (b). In case (a) the friction force was varied over a relatively wit e range. The friction force increases in a grad ual manner until the load ing force becomes equal to 5.5 nN, then a sharper increase is observed . At load s above 9 nN, irregular fluctuations of the friction force are observed . In this case the friction force exhibits hysteresis as the load is d ecreased and 'a osen to revert to its original value. Case (b) correspond s to the regime of small load s. A considerable remanent friction force at the point of d etachment of the probe from the surface and its weak linear increase with increasing load are worthy of note. Such ad epend enced iffers sharply from analogous d epend ences in the case of elastic contacts (see, for example, Fig. 5). (Reprod uced with the permission of Salmeron [43], copyright J C Baltzer AG, 1998.)

coatings, whereas for the $\vec{\sigma}$ iamon $\vec{\sigma}$ – $\vec{\sigma}$ iamon $\vec{\sigma}$ contact, on the contrary, the presence of hum $\vec{\sigma}$ ity results in a $\vec{\sigma}$ ecrease of it (see Ref. [6]).

Tribochemical processes have already found use in nanolithography (see work [90] and references therein), since the regions of tunnelling contacts with a passivated silicon surface und ergo selective oxid ation. On the whole, the study of tribochemical processes on a nanoscale is still in its infancy.

3.4 Formation of dents and scratches, wear

Friction without wear is a consequence of the elasticity of a contact, if the $\dot{\sigma}$ amage-formation threshold is not reached. Energy may also transform into heat in the process of plastic $\dot{\sigma}$ eformation, therefore, the latter plays an important role in $\dot{\sigma}$ etermining the tribological characteristics of materials.

As was already mentioned, images obtained in the contact mode of an AFM cannot reveal the formation of point

 \mathbf{d} effects, therefore, so far it is unclear whether they are form \mathbf{d} or not in the process of scanning in the regime of small load s. If these point \mathbf{d} effects occur, they must mark \mathbf{d} ly affect friction forces. This problem need s special theoretical const eration.

Wear of the probe and sample materials was observed in many experiments (seed iscussion in Ref. [3]). In some cases, after scanning part of surface, d amage was observed at load s above a certain threshold, in other cases the process of wear became tribochemical in character [91]. Of course, ad istinction need s to bed rawn between wear (ord egrad ation) of a surface in vacuum conditions, on the one hand, and in atmospheric conditions, when the processes of oxid ation are d ominant, on the other. In this section we d iscuss wear of clean surfaces only.

As one would expect, the epth of scratches resulting from nanoin entation increases with increasing load. The observation and control of this process for changing load ing forces allow one to study the mechanisms of material fatigue and to d etermine the resistibility of ultra-thin coatings to wear. Since AFM method s make it possible simultaneously to conduct measurements of the ind entation d epth and the value of the normal force, outstanding possibilities are opened up for the investigation of plastic d eformation of materials and surface coatings. Such experiments have revealed an increase in the shearing stress and microhad ness of god films by an of er of magnitude e in comparison with macroscopic samples. However, in some works (see, for example, Ref. [92]) it was noted that hat ness increases with increasing load. Using AFM, one can transfer a nanostructural material from one surface onto another, as wasd emonstrated, for example, in the case of fullerene films.

Friction and wear und er higher load s can be effectively stud is with the use of the technique of controlled multiple slip along a prescribed d irection [24]. In Ref. [24] the formation of scratches and the ad hesive strength of silicon nitrid e, carbon nitrid e and d iamond -like coatings 20 nm thick in the process of ind entation were investigated. A threecornered d iamond ind entation were investigated. A threecornered d iamond ind entation were investigated. In the initial phase of slip, the main mechanism of wear was the 'ploughing' of the surface. However, on increasing the number of scans or the normal load, the process of scratch formation began to pred ominate. Such experiments are of great interest for testing the scratch theory.

The appearance of point^d efects in the process of scanning an AFM probe at small loat s was first pret icter by Schluger et al. [93] who simulater the interaction of an MgO probe with newly-cleaver surfaces of NaCl and LiF. It was assumed that a chemically active OH⁻ group is localizer on the apex of the probe. On subsequent simulation, the formation of vacancies and interstitial atoms on the surface of the sample as well as the movement of ind iver ual ions through the contact area.

The simulation of atomic wear was performed by many authors [67–69, 82]. In these works the formation of at hesive avalanches [82], the plastic creep of atoms into interstitial positions and the extrusion of material in the vicinity of the probe surface [83], and the formation of d islocations [69, 94] were studied. For example, a simulation proced ure for the contact of a Ni (Au) probe with the Au (Ni) surface shows the presence of an instability as the probe approaches the sample to a d istance of about 0.4 nm [4]. In the vicinity of the corresponding point, strong at hesive coupling occurred accompanied by sudd en 'wetting' of the nickel by god' atoms. Lifting the probe from the surface resulted in a const $\dot{\vec{\sigma}}$ erable inelastic $\dot{\vec{\sigma}}$ eformation and $\dot{\vec{\sigma}}$ is ruption of the sample in the contact area [69].

Some new peculiarities of at hesive wear were observer in works [82] for a W (probe) - Fe (sample) system. The authors note several stages of this wear: the d isplacement of surface atoms ahead of a moving probe, phase mixing, the ord ering of probe atoms and their 'sticking' to the surface of the sample. Simulation for ionic crystals (CaF₂) and silicon crystals has revealer a surface-material shift and inter-phase transport [95] as well as the fragmentation of material because of the impact of a probe [96]. The simulation of nickel probe slip over the relatively soft copper surface (whose structure is incommensurable with the structure of nickel) [69] has shown the presence of a peculiarity of stick-slip cycles lying in the fact that each cycle incluit es twoid ifferent processes accompanie by structural transformations: in the first stage of slip one layer of nickel atoms changes its structure to match the copper surface structure, and then, in the second stage, two layers form a new structure (see Section 4.3). Eventually, this results in wear, with a quasi-linear increase of the lateral force at small load s at the stick stage and a sharperd rop at the slip stage. This is in qualitative agreement with experimental AFM d ata (see Fig. 3). At large load s, the stick-slip effect becomes less regular.

3.5 Interfacial lubrication and shear ordering of film structures

Among theoretical problems relating to nanotribology, the problems of interfacial lubrication are most complex, since the correlation of the properties of lubricating materials with at hesion and friction initiate a wealth of new physical effects [6]. There is with e use of lubrication coatings based on selfsupporting multimolecular liquid layers. A more effective method consists in coating the contacting surfaces with chain multilink molecules [4]. Such self-ord ering monolayers can be obtained by eposition of Langmuir – Blod gett (LB) films or by chemical 'integration'. Bestd es, in recent years fullerenes and nanowires have attained with espread application as lubricants.

An extert of d iscussion of the application of AFMs and SFAs in stud ies of lubricating coatings and their structures on shearing and compression can be found in reviews [3, 4], therefore, we well only on the most interesting d etails of the relevant experimental results.

The structure of ultra-thin films strongly d eperd s on the intermolecular forces within a film and its interaction with the substrate. As noted in work [4], the influence of two sold surfaces ad jacent to the film lead s to a vastly greater viersity of inter-phase properties in comparison with the case of only one surface. If the interaction of a sold surface with a liquid interlayer ind uces the coagulation of the latter and the film period ically melts and congeals in the process of slip, then we are d ealing with slip-stick friction of surfaces. Sticking correspond s the coagulation of the film and gives rise to a static friction force. Slip arises when the melting of the film is ind uced by shear, with the result that the friction becomes kinetic in character.

The relative value of intermolecular forces and filmsubstrate interaction forces $\dot{\sigma}$ epend s on the length of the links of chain molecules or on the number of CH₂ (*n*) groups entering into their composition [3]. It is expected that for n < 10 Van $\dot{\sigma}$ er Waals forces between the molecules and a substrate are $\dot{\sigma}$ ominant, and for n > 12 the covalent interactions of the 'head's' of ind ivid ual molecules with one another are more essential. For self-ord ering silane-type structures, it is necessary to take into account both the interaction with the substrate and the interaction of the chains of ind ivid ual molecules. In this case the formation of 'brid ges' Si-O-Si linking at jacent molecules is istorts the structure of the heat parts of the molecules at jacent to the substrate and results in the d isappearance of long-range ord er in the film structure.

Using the mot ulation AFM mot e, Overney et al. (see Ref. [97] and references therein) observed a correlation between friction and the elastic properties of films. Und er load a softer film forms a contact with a larger area and, hence, with larger friction. The molecular structures of films essentially d epend on the applied pressure and temperature. For sharper probes (with a ratius of curvature of about 100 nm), pressures reach values of the ord er of several GPa, therefore, such probes easily pierce films and displace molecules in the lateral d irection. Pressures of the oft er of 10-200 MPa cannot prot uce market structural changes, and the molecules remain in a more or less normal state, bearing the load applied to the cantilever, and the probe slips over the 'heat's' of the molecules. The critical value of the loat ing force $P_{\rm c}$ which can prot uce structural changes in films increases on increasing the ratius of the probe. For thiol molecules on a got surface the original structure of the film is regained after unload ing, but for silanes this is not the case.

One can provide a simple explanation for the lastmention d effect considering the elastic d efformation of a film, on the one hand, and the increase of the area of contact on compression, on the other [3]. The process of d efformation causes the absorption of energy, whereas the increase of the area of a phase interface, on the contrary, provides the generation of energy. The reversibility of the transition for thiol films (after unload ing) is connected with the relatively small number of molecules d isplacing from a region und er the probe in the surround ing medium, since they possess finite lateral compressibility. For silane films on mica, on the contrary, d eformation ind used by the probe and the d isplacement of molecules cause the irreversible d isruption of Si -O -Si brid ges, therefore, the original structure is not regained.

Dynamical structures occurring in the process of lubrication slip of surfaces carrying layers of surfactants and /or polymersd epend on the slip velocity and temperature. This fact is known as the temperature-time superposition principle. High slip velocity and low temperatures are favorable to the coagulation of the films, whereas low velocities and high temperatures cause them to melt [4]. As a result, solid films exhibit interrupted slip-sticking with high friction, and liquid ones shows superkinetic slip of a viscous character with low friction. An intermed iate case corresponds to amorphous structure films with high friction because of the entangling of molecular chains. The results of simulation of these structural changes and phase transformations on the atomic level are in gratifying agreement with experimental results.

Krim and Chiarello [98] studied the influence of structural transformations on the d amping time of motion of ad sorbed krypton films using the quartz crystal microbalance technique. A long slip time is obviously d etermined by low friction. The slip time for sold monolayer structures was found to be larger than that for liquid structures. Being in a sold phase, krypton atoms are 'locked' in a structure incommensurable with the structure of substrate atoms (Au). Therefore, for lack of stable localisation (with a minimum of energy relative to the substrate), the Kr films slip with low friction. For commensurate structures, on the contrary, the friction force turns out to be many $o\vec{x}$ ers of magniture higher [62]. This behaviour is opposite to that which is inherent in the above-construction of the layers of chain organic molecules.

A number of analogous results relating to the friction of at sorbet films were obtained in numerical MD experiments. In particular, the existence of transitions from film structures incommensurable with substrates to commensurable ones, strongly affecting the value of the friction force, was confirmer. For example, Tamura et al. [99] considerer a realistic mot el of friction between talc (001) surfaces (at a pressure of 1 atm and a temperature of 300 K). The total number of atoms was 570. The authors took 7 atomic layers for each film and imposed a period ic bound ary condition in the plane of slip (xy). Setting the velocity (50 m s⁻¹) of the atoms of the upper film (or of a part of this film), they analyzet the movement of the centre of mass. It was found that friction is high in the case of commensurable structures with zero angle of d isorientation and low for incommensurable structures with an angle of $\dot{\sigma}$ isorientation of 30°. The relation of the friction force with the fluctuations of the interphase interaction potential was also fount .

In work [100] the MD simulation of the motion of a monoatomic a^{\dagger} sorbet layer on a crystalline surface (for a conventional motel situation) was conducted. The motel sample included of 5760 atoms, and the temperature was fixed below the melting point. The main result of this work was the d etection of the effect of 'locking' motion for a short time interval (about 0.1 nsec), with external forces being unchanged. A necessary condition for 'locking' is the presence of incommensurability and structural d egeneration which promote the reconstruction of the film structure and its transfer to another equivalent mod ification.

The role of electron and phonon excitations in the problem of the \dot{d} ynamical friction of $a\dot{d}$ sorbed films has been studied theoretically by many authors. We will revert to the d iscussion of these questions in Section 4.5.

3.6 Metallic nanocontacts

In a number of works, synchronous measurements of load ing forces and electric current in conducting metallic nanocontacts between a probe and a sample fabricated from the same material were performed. The measurements were conducted both at room temperature und er atmospheric conducted in high vacuum [70, 101]. Discrete jumps of the conductivity of the nanocontacts corresponding to the relaxation of the forces of probed etachment from the surface were measured. The value of each jump of conductivity was of the ord er of the value of the conduction quantum $2e^2/\hbar$ and each jump of the force was $\Delta F = 1.5 \pm 0.2$ nN. Such changes of conductivity and the force of interaction would be expected as a one-atom contact is d isrupted (see Section 4.3). Jumps of conductivity were also d etected with the use of STMs.

The existing theoretical explanation of the $\hat{\mathbf{d}}$ iscrete change of cord uctivity relates the mechanism of this effect with the atomic rearrangement of the contact area. This rearrangement includes the stage of elastic expansion and the stages of plastic creep and $\hat{\mathbf{d}}$ isruption of contact brid ges observed with a period icity of the interlayer $\hat{\mathbf{d}}$ istances in a forming contact brid ge. The formation of extended brid ges between the probe and sample lead s to hysteresis of the 'force-load' ' $\hat{\mathbf{d}}$ ependence in the lowering-lift mode. Moving the probe away from the surface causes const erable $\dot{\sigma}$ eformation of the sample with counter movement of layers of the probe and sample materials at jacent to the contact as well as the formation and $\dot{\sigma}$ isruption of a contact brid ge. Hence, the hysteresis of the 'force-load' ' $\dot{\sigma}$ epend ence is a consequence of the isruption of the sample. This conclusion is supported by the MD simulation [69].

This picture is rear ily illustrater with the example of a spoon slowly being puller out from half-car is honey. In the initial state (when the spoon is ipper into the honey) the honey surface is smooth and its grainy ('atomic') structure is not seen. On the contrary, when the spoon begins to detach, we can clearly see a layerer structure of ind ivit ual 'grains' in the contact brid ge (stream) connecting the spoon with the bulk of the honey. In this case the variations of the velocity of the slowly flowing stream associater with the d isruption of liquid interlayers between the ind ivid ual grains of honey are visible.

A result of great importance, obtained in experiments [70, 101], is that the value of the contact stiffness turns out to be comparable with estimates following from the macroscopic contact theory (Fig. 8). In the case when the voltage across the contact is constant, current and contact cond uctivity turn out to be proportional to the area of the contact for an arbitrary cond uction mechanism [3, 43]. This allows one to use the measurements of current and cond uctivity for relative calibration of the area of a nanocontact.



Figure 8. Set of current–voltage characteristics for tunnelling current versus load ing forces (up to $1.7 \,\mu$ N) measured in the process of d isplacement of the sample (only every seventh curve is shown). Inset: tunnelling current through the contact as a function of the applied load at a constant voltage. One can recognize that the experimental values of the tunnelling current (proportional to the area of the contact) are in good agreement with the DMT theory. The JKR approximation (the correspond ing curve is shown only for the first set of measurements) obviously ind equately d escribes this stiff contact (tungsten carbid e–d iamond). (Reprod uced with the permission of Salmeron [72], copyright of the American Physical Society, 1998.)

3.7 Friction of films adsorbed on the surfaces of superconductors

In a recent paper [18] Krim et al., using the QCM technique, found a sudd en d ecrease (by about one half) of the d ynamical friction force acting on the layer of nitrogen molecules physically \vec{at} sorbet on the surface of a leaf film as the temperature was \vec{at} ecreased below the superconducting transition point of leaf. Persson and Tosatti [102] \vec{at} iscussed conceivable physical reasons for this effect associated with an electron contribution to \vec{at} ynamical friction.

In their experiment a lear film with an ar sorber layer of nitrogen molecules (1.6 ML in thickness) cooler below $T_c = 7 \text{ K}$ was user. The sharp jump of the quartz-oscillator d'amping time observer is obviously d'eterminer by the transition of lear into the supercond ucting state. Analysing the role of electron friction, the authors of work [102] note that accor ing to the existing notions (at normal temperatures) such a sharp change in friction should not to be observer because of the continuous change of the number of electrons going into the supercond ucting cond ensate, and this is inconsistent with experiment.

At these temperatures, the $a^{\hat{j}}$ sorbet film of nitrogen molecules must be solar and is likely to have a structure incommensurable with the substrate structure. Such a structure must exhibit low friction. However, there is no clear reason for the fact that the coagulation of the film takes place just at the superconducting transition temperature.

Some constit erations can be applied to the role of fluctuation-electromagnetic friction (see Section 4.5). Taking into account the fact that in the process of interaction of a krypton film with lead (in the normal state) the absorption of electromagnetic waves in the frequency region near 10^{12} Hz, corresponding to the energy gap of lead, contributes essentially to friction (giving about one-half of the total), one can assume that the normal-superconducting transition of lead will result ind ecreasing friction.

In summary it should be sald that even at normal temperatures the relation between \dot{d} ifferent contributions in \dot{d} ynamical friction continues to remain the subject of intensive \dot{d} iscussion (see Section 4.5). Therefore, the problem concerning the theoretical interpretation of the effect [18] offers const erable scope for \dot{d} ifferent viewpoints.

3.8 Triboemission of particles, electromagnetic and acoustic waves

In work [15] an investigation of triboelectromagnetic phenomena ford ifferent slip contacts user in magnetic record ing d evices (for writing information on hard d isks) was und ertaken. The yield of charger particles and photons was measurer in the process of slip of a d iamond probe with a rad ius of curvature of 10 microns at a normal load ing force of 0.5 N and a slip velocity of $2-7 \text{ cm s}^{-1}$ (und er atmospheric cond ition). The results of these experiments revealed a correlation pointing to an increase of the yield of particles with increasing cond uctivity of the surface material (Fig. 9).

To estimate the elastic energy stored in a typical nanotribocontact, one can use the following relationship of the Hertz theory: $U = 0.15P^{5/3}/R^{1/3}E'^{5/3}$ eV, where *P*, *R*, *E'* are measured in nN, nm and TPa, respectively. Then at P = 100 nN, R = 50 nm and E = 0.1 TPa one obtains a value of about 415 eV. On the other hand, the formation of scratches and at hesive processes occurring on the newlycleaved surfaces of ielectric materials may be accompanied by the appearance of strong local electric field s capable of further accelerating charged particles.

One can assume that charger particles former in the process of friction of a probe are capable of escaping from



Figure 9. Correlation between the intensity of charget particles emitter from the probe-surface contact area and the conductivity of solid's. The measurements were conducted in air for a diamond probe with a radius of 10 μ m at a load ing force of 0.5 nN and a slip velocity of 7 cm s⁻¹. The arrows show that the values of resistance are beyond the limits of the instrument sensitivity. (From work [15].)

the surface and may be $\mathbf{\hat{c}}$ etected only in the event that the $\mathbf{\hat{c}}$ ischarge time for arising electric field s is sufficiently long. For metals, this time is about 10^{-15} s, therefore, even fast electrons, having velocities of the or $\mathbf{\hat{c}}$ er of the Fermi velocity $(2 \times 10^8 \text{ cm s}^{-1})$, have no time to escape from the surface. Hence, the escape of positive and negative particles observed for metals is likely to be $\mathbf{\hat{c}}$ etermined by the chemical reactivity of the impaired (by the probe) surface interacting with surrourd ing air molecules.

For semicord uctors and $\dot{\sigma}$ ielectrics this is not the case, and a construction of particles may escape from the surface in the process of field $\dot{\sigma}$ esorption or evaporation. These notions give a qualitative explanation for the observed $\dot{\sigma}$ epend encies of the yield of particles in the case of conductors and $\dot{\sigma}$ ielectrics (see Fig. 9).

Obviously, there is a need to conduct more d etailed experiments of this type tod etermine the peculiar features of the corresponding mechanisms of emission in vacuum. First and foremost it makes sense to measure the energy spectrum of escaping particles. Assuming that the yield of particles is proportional to the area A of an actual contact, one can estimate a relatived ecrease of the yield when going from a micro- to a nanoscale. In the Hertz approximation, for the area of the contact we have $A \sim (PR)^{2/3}$, where P and R are the normal loading force and the radius of curvature of the probe, respectively. Then at P = 100 nN and R = 30 nm, one obtains that the yield of particles is of the ord of that observed in work [15]. Such a yield can be measured with the use of more sensitived etectors.

The effects of electron nanotriboemission obviously have much in common with exoelectron emission observer in $\dot{\mathbf{a}}$ ifferent conditions. The measurement of this emission is one of the promising method is for surface studies. The AFM method gives excellent possibilities to record the spectra of exoelectron emission, occurring on normal and lateral load ing of nanotribocontacts, in synchrony with sample scanning. As far as is known, such measurements have not been conducted.

The authors of work [103] observed the acoustic emission occurring in the process of slip of magnetic record ing head s in

High-spect processes taking place in the contact area may generated ifferent types of rad iation, therefore, it is ad vantageous to use the corresponding effects in studies of nanotribological actions on a surface.

In conclusion of this part of the review we formulate the most important problems of experimental character whose solution must refine the und erstand ing of the physics of nanotribocontacts.

To obtain solt quantitative information using AFMs, it is necessary to perform *in situ* force calibrations taking into account concrete instrumental peculiarities, such as normalto-lateral signal relationship, nonlinearity of piezoceramics, creep, hysteresis and so on.

One of the primary problems is the $\dot{\mathbf{q}}$ etermination of the characteristics of a probe, its shape, structure and chemical composition. It is necessary to combine and apply $\dot{\mathbf{q}}$ ifferent methods for $\dot{\mathbf{q}}$ etermination and control of its form as well as the combinations of $\dot{\mathbf{q}}$ ifferent materials and the geometry of contacts. In this connection the methods of $\dot{\mathbf{q}}$ etermination of probe shapes and the area of contacts based on the measurements of contact conductivity and the yield of the inverse scattering of a low-intensity ion beam in Rutherford scattering are noteworthy. The unknown properties of probes can be revealed through comparative analysis of their characteristics. In this respect materials of considerable promise for probes are single fullerenes and nanowires.

It makes sense to conduct more detailed studies of the stick-slip effect and the mechanism of ad hesive wear over a wider interval of slip velocities for d ifferent combinations of materials. There are a number of scantily studies aspects of this effect associated with the character of periodicity, the threshold of the slip start and anisotropy, the criteria of antifriction slip, the formation of point d effects, the d etermination of the role of the structural commensurability effect and fluctuations of the phase interaction potential.

The furt amental processes of energy issipation because of friction remain scantily studied. There is, in particular, a need for the d etermination of the peculiar features of the d vnamical mechanism of electron (electromagnetic) and phonon friction. The mechanisms of noncontactor ynamical friction may be studied not only with the use of the QCM technique, but also in the vnamical more of an AFM. It is necessary to d etermine the d epend encies of d ynamical friction forces on the velocity, temperature, probe ratius and its d istance from the surface, the applied load, the d ielectric properties of materials, the chemical composition and structure of a surface, the humd ity (composition of surround ing atmosphere) and so on. In connection with the QCM technique and d etermination of the mechanisms of $\dot{\mathbf{d}}$ ynamical friction, it makes sense to study the $z\dot{\mathbf{d}}$ epend'ences of the d'amping time of ad sorbet films using at sorbet layers with tifferent timensions and types of molecules.

There is a new for more intensive studies of tribochemical, triboelectromagnetic and triboacoustic effects. In particular, the investigation of the sensitivity of normal and lateral forces to the chemical contrast is of great interest. Comprehensive information on the structure and properties of contacts can be obtained from measurements of the triboemission of particles on the nanostructural level.

4. Theory of friction forces in nanotribocontacts

4.1. Contact-mechanics approximations and comparison with AFM data.

Although the basic contact-mechanics approximations were $\dot{\mathbf{q}}$ eveloper for the escription of macrocontacts [12 27, 73], in many cases these approximations allow one to obtain realistic estimates of some values measurer with the use of an AFM on the atomic level, as was shown in a number of recent works [3, 32, 35]. Therefore, before proceering to experimental ata, we will briefly review basic theoretical relationships.

All the mot els constit erei d'escribe an elastic contact of two convex bot ies with rat ii of curvature of $R_{1,2}$. The oft est known version of the theory is the Hertz more el which d oes not take account of at hesive forces. The Johnson - Kent all -Roberts mot el allows for at hesion in the contact approximation through incorporation of the a^{\dagger} hesion work γ [see Eqn. (3.1)]. The Deryagin – Muller – Toporov approximation [27] takes into account not only at hesive forces themselves, but also their finite ratio of action through the parameter z_0 correspond ing to an equilibrium istance between two plane surfaces. In this case the shape of the contact area remains it entical to that for the Hertz mot el and, in add ition, the DMT theory at equately describes the contact of stiff surfaces with long-range attractive forces. The JKR mot eld escribes a contact of two surfaces made from soft materials and /or with large rat ii of curvature.

In the case when the interaction between the atoms of the bot ies is given by the Lennard -Jones potential, the relationship betweend ifferent versions of the theory is d etermined by the universal imensionless parameter

$$\mu = 2.92 \left(\frac{\gamma^2 R}{\tilde{E}'^2 z_0^3}\right)^{1/3},\tag{4.1}$$

where E' is the red used mod ulus of elasticity [see Eqn (3.3)], and $R = R_1 R_2 / (R_1 + R_2)$ is the red used rad ius of curvature. The 'Hertz' type solution is realized at $\mu = 0$; for $\mu < 1$ (actually for $\mu < 0.5$) the DMT limit hold s, and $\mu > 1$ correspond s to the JKR limit.

For the intermed iate case (at $\mu \approx 1$), the theory was generalized by Maugis and Dagi ail (M-D) [104]. Recently, Barthel examined the case of an arbitrary form of the interaction potential (see the second reference in Ref. [105]).

For nanotribology, of prime importance are formulas for the rat ius of the contact area a and the at hesive friction force Fd etermined by the second term in expression (2.5). These formulas can be written in the following approximations:

a) The Hertz approximation

$$a = \left(\frac{0.75RP}{E'}\right)^{1/3},\tag{4.2a}$$

$$F = \pi \tau a^2 \,; \tag{4.2b}$$

b) The JKR approximation

$$a = \left(\frac{9\pi\gamma R^2}{8E'}\right)^{1/3} \left(1 + \sqrt{1 + \frac{2P}{3\pi\gamma R}}\right)^{1/3},$$
 (4.3a)

$$F = \pi \tau a^2 \,, \tag{4.36}$$

and the critical force of probed etachment is determined by expression (3.3);

c) The DMT-approximation, in which a is \dot{c} etermine \dot{c} by formula (4.2a) and the friction force is

$$F = \pi \tau \left(\frac{0.75R}{E'}\right)^{2/3} (-2\pi R\gamma + P)^{2/3}, \qquad (4.4)$$

and the critical force of $\dot{\mathbf{c}}$ etachment is obviously equal to $P_0 = -2\pi R\gamma$.

In all the formulas presented above τ is the shearing stress as before. In the M-D approximation the friction force is d etermined by formula (4.3b) with an add itional multiplier (> 1) being obtained from a transcerd ental equation [104]. As follows from formulas (4.3a) and (4.3b), at the point of d etachment of the probe from the surface the rad ius of the contact area and, correspond ingly, the minimum value of the friction force remain finite [see Eqn (3.3)]. This is also true for the M-D approximation. In the case of the DMT approximation, at the point of probed etachment the friction force and the rad ius of the contact are zero. Thus, there is no hysteresis of the correspond ing quantities.

Direct proportionality between the friction force and the area of the contact is observed both in AFM and SFA experiments. In experiments with the use of an SFA (for mored etails, see Ref. [3]), a linear pressured epend ence of the shearing stress was found in the case of an LB film sand wiched between mica plates:

$$\tau = \tau_0 + \frac{\alpha P}{\pi a^2} \,, \tag{4.5}$$

where $\tau_0 a \mathbf{n}^{\dagger} \alpha$ are empirical parameters.

For \mathbf{d} ry' contacts, $\tau \mathbf{d}$ oes not \mathbf{d} eperd on *P*. This is support \mathbf{d} by the results obtain \mathbf{d} in work [47], where the friction forces for a silicon nitr \mathbf{d} e probe on the mica surface were measured. In this experiment the friction force (as a function of the load) was measured immediately following the measurement of the contact stiffness. Using expressions (4.3b) and (2.4), it is easy to obtain the following formula for the shearing stress:

$$\tau = \frac{64G'^2 F}{\pi k_c^2} \,, \tag{4.6}$$

where k_c is the contact stiffness. As it turner out [47], the friction force *F*, the contact stiffness and , in accord ance with formula (4.6), the shearing stress d d not d epend on the load, with the exception of the region of d etachment of the probe from the surface where the effect of capillary forces manifested itself because of the presence of humd ity (55%).

It follows from formulas (4.2)-(4.4) that the load $\dot{\mathbf{d}}$ epend ence of the friction force is $\dot{\mathbf{d}}$ etermined by two experimentally measured parameters: critical values of the $\dot{\mathbf{d}}$ etachment force and the friction force or, which is the same, any pair of values (P, F) on the F(P) curve. In the case of an add itional epend ence between τ and y (see Section 3.2), the only ind eterminate parameter of the mod el is the value of the red used mod ulus of elasticity E' or the probe rad use R. This makes it possible to use the AFM for d etermination of the mechanical, geometrical and ad hesive characteristics of contacts.

The results of the best known experiments, where the F(P)d eperd ences for elastic nanocontacts in vacuum were measured, are presented in works [35, 43, 72]. To interpret the $\dot{\mathbf{a}}$ at a obtain $\dot{\mathbf{a}}$, the authors use $\dot{\mathbf{b}}$ the following approximations: DMT — in the case of a tungsten carbiner probe on a (111) $\dot{\mathbf{a}}$ iamon $\dot{\mathbf{a}}$ surface [72] (this is the case of the stiffest contact, see Fig. 10); M – D — for the silicon – NbSe₂ contact [35]; JKR — for the Pt-mica contact [43] (Fig. 11). Some measure $\dot{\mathbf{a}}$ and calculate values relating to these experiments are listed in Table 1.



Figure 10. Experimental and theoretical (corresponding to the DMT $m\sigma$ el) d ependience of the friction force on the loading force for a very stiff contact between a tungsten carbid e probe and a (111) d iamond surface treated by hyd rogen. Inset: forced istance curve. The experimental value of the d etachment force (-7.3 nN) correlates very well with the theoretical value predicted by the DMT curve. (Reprod uced with the permission of Salmeron [72], copyright of the American Physical Society, 1998.)

Table 1. Empirical parameters measured with the use of AFMs in the case of d ry' elastic nanotribocontacts in vacuum. Pairs of numbers in the last column correspond to maximum and minimum experimental values obtained in the process of friction scanning. (Reprod uced with the permission of Salmeron [72], copyright of the American Physical Society, 1998.)

Work	[72]	[35]		[43]	
Model	DMT	M - D		JKR	
System	WC – diamond (111)	$Si-NbSe_2$		Pt-mica	
E', GPa	460.1	40.3		44.8	
z_0 , nm	0.2	0.2		0.2	
<i>R</i> , nm	110	12	45	140	
F_0 , nN	0	2.5	8.0	210	7.9
$-P_0$, nN	7.3	7.0	21.9	267	12
τ, GPa	0.238	0.61	0.66	0.921	0.27
$\gamma, J m^{-2}$	0.0106	0.099	0.087	0.404	0.019
μ	0.0065	0.61	0.58	0.38	0.07

Analysis of the above $\dot{\sigma}$ at a shows that only experiments [35, 72] satisfy the conditions for applicability of the corresponding approximations (M-D and DMT) relative to the value of the μ parameter. Strictly speaking, in work [43] the μ value corresponds to the DMT or M-D approxima-



Figure 11. Characteristic 'friction force – loat ing force' curve for a platinum coater probe on a newly-cleaver mica surface in vacuum uring a single scan along a given irection (see also Fig. 5). On the horizontal axis the external loat ing force (which is proportional to the vertical isplacement of the cantilever) is plotter. The zeroth point corresponses to the off-contact position of the probe. On the vertical axis are the averager critical values of the lateral forces for each value of the load ing force (see Fig. 3). Note the nonlineard eperd ence of the friction force on the load and and intervalue of the friction force at the point of are sufficient of the route is plotter in accord ance with the JKR approximation using the values of the friction force and the detachment force at the critical point of the contact. The lower part of the theoretical curve correspond s to unstable cond itions, since the contact disappears at point A. (Reproduced with the permission of Salmeron [43], copyright of the American Physical Society, 1998.)

tions, however, the form of the experimental curves F(P) is not $\vec{\sigma}$ escribet by these mot els and fits the JKR mot el. The authors believe that the monotonic $\vec{\sigma}$ ecrease of the $\vec{\sigma}$ etachment forces and the critical friction forces for successive scan cycles is related to possible changes of the phase interface, and structural and chemical effects.

One important d etail should be not d concerning experiment [72], namely, the very small calculated value of the shearing stress (0.238 GPa), even though the corresponding contact is the stiffest among all the contacts d iscussed.

If relationships between the macro- and microscopic values of physical quantities remain about the same, then it should be expected that the corresponding value of τ must be, as a minimum, an ord er larger. In this respect the results of work [35] show better agreement. Indied, the measured value of τ and the macroscopic formula $G \approx 29\tau$ give an estimate for the shearing stress in good agreement with its macroscopic value.

It is possible that the und erestimate of the shearing stress results from the illegality of extrapolation of the DMT d epend ence to the region of zero friction forces (see Fig. 10). However, in the experiment und erd iscussion at the critical force of d etachment (-7.3 nN) the friction force was not d etermined and its minimum value was measured only at a normal force of -2 nN. Thus, it is possible that, even though the DMT approximation correctly d escribes the F(P)d epend ence in the range of load s from -2 to 12 nN, the minimum friction force in contrast with the theoretical prediction d oes not actually red uce to zero. In this case, to test the valid ity of the mod el, it is necessary to measure the F(P)d epend ence for P < -2 nN using softer cantilevers.

Another subject for \dot{c} iscussion concerns the interpretation of the results of work [43]. Despite the fact that the JKR approximation provides good agreement with the experimental F(P) d ependences, the value of the μ parameter seems too small for this model to be considered as being ad equate to experimental conditions. In this connection d oubts are cast upon the correctness of using formulas (3.2), (3.3) and hence the correctness of the above-mentioned relation $\tau \propto \gamma^{0.44}$ (see Section 3.2).

The results of work [35] reveal an interesting $\dot{\sigma}$ etail as well: as follows from Table 1, the $a\dot{\sigma}$ hesion work $\dot{\sigma}$ ecreases with $\dot{\sigma}$ ecreasing the rat ius of the probe, whereas the shearing stress, on the contrary, increases. Thus, we see that τ is inversely proportional to γ . None of the existing theoretical mot els can explain this result.

The above $\dot{\sigma}$ iscussion shows that even in the simplest case of $\dot{\sigma}$ ry' elastic nanocontacts, the classical $\dot{\alpha}$ hesive friction more els may come into conflict with experiment. Such contrad'ictions may be $\dot{\sigma}$ etermine $\dot{\sigma}$ by experimental errors and /or by the influence of the atomic structure of surfaces and other effects which are ignored by the contact theory.

Linear F(P) d'epend ences which look nothing like those d'escriber by the contact-mechanics approximations were observer in experiments with alkaline-halod crystals [71], GeS (Shwarz et al., [88]), LB and Au films, polytetrafluoroethylene (PTFE) films (PTFE is a polymeric lubricating material) as well as with multilayer structures baser on PTFE and silicon nitrid e (Xin-Chun Lu, [88]). In the case of KCl and KBr crystals, these epend ences are shown in Fig. 7. There is no theoretical explanation for these curves.

4.2 Simple models of friction forces, the stick-slip effect and modelling surface images in the contact AFM mode

The mechanical model of lateral movement of the probe over a surface is based on early work by Tomlinson [61] and the ind epend ent oscillator approximation. This model is schematically illustrated in Fig. 12 taken from the work by Zworner et al. [56]. A probe is elastically attached to a bod y of mass Mconnected to a cantilever via a spring of stiffness c. It interacts with the sample through a period ical potential U(x), where xis the lateral coord inate of the probe. The cantilever moves with a constant velocity $V_{\rm M}$. Ind epend ently of concrete microscopic mechanisms, the energy d issipation per unit



Figure 12. On the left: a simple mot el of probe slip along an atomically smooth surface; x_t is the lateral cook inate of the probe elastically attached to a bod y of mass M through a spring of stiffness c_x . Interaction with the surface is effected through a period ical potential $U(x_t)$ having a period a. At $x_t = x_M$ the spring is unstrained. When slipping, the bod y M moves with a velocity V_M in the x^2 irection. On the right: the movement of the probe in a surface potential. If condition (4.8) is fulfilled, the movement is of a stick-slip character, and the probe 'jumps' from one point (of the minimum of the potential energy) to another. (Reprod uced with the permission of Holscher [56], copyright of Springer-Verlag, 1982).

time is d etermine d by the d amping factor proportional to the velocity, whereas the friction force is in d epend ent of the velocity.

Obviously the point probe mor el gives an oversimplifier d'escription of the contact which is actually former from several hund red s or thousand s of atoms. In more complex mor els of friction, the region of the contact area is consti ered as an aggregate of a finite number of bound (not bound) oscillators. Despite their simplicity, mor els of this type quite successfully explain the spasmor ic movement of a probe and allow one to mor el AFM images in the contact lateral mor e [106].

Using the sinusoid al approximation for the period ical force acting between the probe and the surface, the equation for probe movement in the one d imensional case can be written in the form [56]:

$$m\frac{\dot{\mathrm{d}}^{2}x}{\dot{\mathrm{d}}t^{2}} = c(x_{\mathrm{M}} - x) - U_{0}\frac{2\pi}{a}\sin\left(\frac{2\pi}{a}x\right) - \gamma\frac{\dot{\mathrm{d}}x}{\dot{\mathrm{d}}t},\qquad(4.7)$$

where *m* is the effective mass of the oscillator, $x_{\rm M} = V_{\rm M}t$ is the equilibrium position of the unstrainer spring at a moment *t*, and *a* and *y* are the lattice perior and the d amping parameter, respectively. Solving equation (4.7) for x(t), one can obtain the value of the lateral force acting on the probe: $F = c(x_{\rm M} - x)$. The d issipative friction force is d eterminer by averaging the lateral force over time, $F_{\rm d} = \langle F \rangle$. If $V_{\rm M} = 0$ and the probe is in the state of stable equilibrium, then a critical cond ition for the start of the spasmod ic movement of the probe is a small value of the stiffness of the contact:

$$c < -\frac{\dot{\sigma}^2 U}{\dot{\sigma} x^2} = \frac{4\pi^2 U_0}{a^2} \,. \tag{4.8}$$

In such a model, friction occurs only as the result of movement and is velocity-independent. For high velocities, 'viscous' d'amping d'ominates and the friction force is proportional to the slip velocity, $F_{\rm ff} \approx \gamma V_{\rm M}$.

In the case of two $\dot{\mathbf{q}}$ imensional movement of the probe, equation (4.7) is generalized through incorporation of two effective masses, stiffnesses and $\dot{\mathbf{q}}$ amping parameters correspond ing to the x and y $\dot{\mathbf{q}}$ irrections [57].

In the case of high-oriented pyrolitic graphite (HOPG) being a test material for AFM, the potential of the interaction of the probe with a surface is approximated by the following model expression:

$$U_{\text{HOPG}}(x, y) = -U_0 \left[2 \cos\left(\frac{2\pi}{a} x\right) \cos\left(\frac{2\pi}{a\sqrt{3}} y\right) + \cos\left(\frac{4\pi}{a\sqrt{3}} y\right) \right], \qquad (4.9)$$

where a = 0.246 nm, $U_0 = 0.5$ eV. Fig. 13 shows the experimental and calculated (computer simulated) d istributions of lateral forces acting on an AFM probe on an HOPG surface [57]. The structure of the calculated force d istributions is explained by the peculiarities of probe movement in the SS mode (Fig. 14). This figure shows that the probe moves spasmed ically and is held back longest at the points of the minima of the potential correspond ing to the centres of hexagons in the graphite lattice, 'jumping' over its maxima which correspond to the positions of



Figure 13. Comparison of experimental and calculated forced istributions (scan area 2 nm \times 2 nm); (a) and (b) correspond to the experimental d ata obtainer with the use of an AFM on a newly-cleaver surface of HOPG. The experimental lateral-force $\dot{\mathbf{d}}$ is tributions in the scan $\dot{\mathbf{d}}$ irection F_x (a) and transverse to this d irection F_{ν} (b) correspond to work [63]. Theoretical force d istributions corresponding to the model d escribed in the text are given for F_x (c) and F_y (c). A comparison between the figures shows that mot elling even reprot uces structural irregularities at the instant of the slip start (at the left of the images). The d istances between in ivit ual maxima (0.246 nm) are the same on both the experimental and theoretical images. The scand irection makes an angle of 7° with the $[\bar{1}2\bar{1}0]$ axis of the (0001) graphite surface. (e) The maxima of the theoretical forced istributions are indicated by points for the F_x projection and by sold lines for the F_y projection. A shift between them is seen. A similar phase shift between lateral forces in the scand irection and transverse to it was first observed by Ruan and Bhushan. (Reproduced with the permission of Holscher [57], copyright of the American Physical Society, 1998.)

carbon atoms. Fig. 14a also gives an explanation of the $\dot{\sigma}$ isplacement of some points of the probe which 'stick' to the surface relative to the minima of the potential. Physically, this $\dot{\sigma}$ erives from the fact that after each microslip the probe cannot stop at once and und er its own momentum 'rushes by' the point of equilibrium.

The effective masses and stiffnesses of springs in the cited works satisfy the condition for critical amping: $\gamma = 2\sqrt{cm}$. Without this assumption the lattice perior icity of the SS effect fails and an irregular slip with multiple 'jumps' is observed'.

It follows from calculations that the $\dot{\sigma}$ issipative friction forces $\dot{\sigma}$ o not $\dot{\sigma}$ epend $\dot{\sigma}$ on the slip velocity for $V < 10^{-2}$ cm s⁻¹. At high velocities, viscous friction begins to $\dot{\sigma}$ ominate. This is in good agreement with the experimental measurements of the friction forces on $\dot{\sigma}$ iamond, graphite and amorphous carbon films [56]. True, the velocities studied in these experiments ranged from $2 \times 10^{-4} < V < 2.5 \times 10^{-3}$ cm s⁻¹. There is no question that such experiments should be carried out over a wid er range.

In recent work [65] Johnson and Wood house generalized this model through incorporation of an additional stiffness of the contact k_e , since the assumption of critical amping of an elastic cantilever is unrealistic. The equivalent one dimensional ynamical system considered in this work is shown in Fig. 15a and the corresponding ynamical equation takes the form [65]:

$$m\frac{\dot{\mathbf{d}}^2 x}{\dot{\mathbf{d}} t^2} + \gamma \frac{\dot{\mathbf{d}} x}{\dot{\mathbf{d}} t} = T_0 \sin\left(\frac{2\pi}{a}s\right) - k_l x\,,\tag{4.10}$$

where $s = V_M t - x - z$ is the tangential microslip of a sample relative to a probe. Accost ing to Fig. 15b, the value of the



Figure 14. Twod imensional istribution of the potential $U(x_t, y_t)$ on a surface of graphite (scan area $2 \text{ nm} \times 2 \text{ nm}$) and a typical calculated trajectory of probes lip along the surface. The time separation between the portions of the d otted ine is $\Delta t = 0.1 \text{ ms}$, the scan velocity is equal to $V_M = 40 \text{ nm s}^{-1}$. The figure confirms the twod imensional character of the stick-slip effect: the probe moves with a iscrete step and most of time stays at the positions of the minima of the surface potential (d ark areas) (a). The light triangles show the *A* and *B* positions of carbon atoms with and without neighbours on the next nearest atomic plane in the lattice structure of graphite; these positions form hexagons (typical for the graphite structure) with a side length of about 0.142 nm. The d ark spots characterize the rest time of the probe at the correspond ing points of the surface (time resolution 512×512 d ots). As is seen from this figure, the probe is held back longest at the centres of the hexagons. Hence the movement of the tip of an AFM probes the points of minima of the surface potential rather than an 'atomic' contrast (b). (Reprod uced with the permission of Holscher [57], copyright of the American Physical Society, 1998.)

microslip is

$$s = V_{\rm M}t - x - \frac{1}{k_{\rm c}} T_0 \sin\left(\frac{2\pi}{a}s\right).$$
 (4.11)

In the quasi-static case (at $\dot{\sigma} x/\dot{\sigma} t = \dot{\sigma}^2 x/\dot{\sigma} t^2 = 0$) x is obtained from Eqn (4.10) and Eqn (4.11) takes the form

$$s = V_{\rm M}t - \left(\frac{1}{k_{\rm c}} + \frac{1}{k_{\rm l}}\right)T_0 \sin\left(\frac{2\pi}{a}s\right)$$
$$= V_{\rm M}t - \frac{1}{k_{\rm e}}T_0 \sin\left(\frac{2\pi}{a}s\right). \tag{4.12}$$

On introl ucing new variables

$$S = \frac{s}{a}, \quad X = \frac{x}{a}, \quad Y = V_{\rm M} \frac{t}{a}, \quad Z = \frac{z}{a},$$
$$K_{\rm c} = \frac{ak_{\rm c}}{T_0}, \quad K_l = \frac{ak_l}{T_0}, \quad q = \omega_l t, \quad \delta = \frac{\gamma \omega_l}{2k_l} \left(\omega_l = \sqrt{\frac{k_l}{m}}\right)$$

equations (4.10) and (4.11) are brought into normalized form

$$F_{\rm c}(S) = \sin(2\pi S) = K_l \left(\frac{\dot{\sigma}^2 X}{\dot{\sigma} q^2} + 2\delta \frac{\dot{\sigma} X}{\dot{\sigma} q} + X \right), \qquad (4.13)$$

$$S = Y - X - \frac{1}{K_{\rm c}} \sin(2\pi S) \,. \tag{4.14}$$

Figure 15c shows schematically the resulting change of the lateral force $F_c(S) = \sin(2\pi S)$ obtained from the numerical solutions of equations (4.13) and (4.14) and Fig. 15t its d epend ence on the isplacement of the probe.



Figure 15. Lateral AFM mœⁱ e. The torsion \hat{a} eflection of the cantilever through an angle θ results in a lateral \hat{a} isplacement *x*; *z* is the contact \hat{a} isplacement; *s* is the value of slip (a). Equivalent \hat{a} ynamical system: k_l and *m* represent the stiffness and equivalent mass of the cantilever, k_c is the contact stiffness (b). Sinusod al change of the friction force F_c . The contact spring loses its stability at point *E* and then executes transition oscillatory motion about the position of equilibrium. The start of this motion correspond s to point *N* with a maximum \hat{a} effection to point *M* (c). Dependence of the lateral force on the \hat{a} isplacement *Y* reflecting a sawtooth character of the stick–slip effect \hat{c}). (Reproduced with the permission of K Johnson [65], the copyright of J C Baltzer AG, 1998.)

Segment OE corresponds to the stable quasi-static position of the probe. At point E an instability occurs and the cantilever begins to move in accord ance with Eqn (4.13). At $F_c(S) = -K_c$, the contact spring loses its stability and the probe 'jumps over' to point *B*. Because of the small mass of the spring, the correspond ing relaxation time is of the ord er of 10^{-12} s that is much less than the period of the cantilever oscillation. Therefore, the elastic energy rapid lyd issipates via phonon and electron excitations. Besti es, $X_B = X_A$, $d X_A/d t = d X_B/d t \approx 0$, and the efformation of the contact spring is equal to $F_c(S)/K_c$. If the effection of the oscillator at point *M* allows it to reach the point of instability *E'* correspond ing to the next cycle of microslip, then before stopping the probe 'rushes by' two or more period's. There are no multiple jumps, if $S_M < S_{E_1}$. Thus, necessary cond itions for this are $K_c > 2\pi$, $K_l > 1.9$. In any case there are no jumps, if $K_l > 0.75K_c$ [65].

The $\dot{\sigma}$ issipative friction force can be calculated on the stable segment of the 'force- $\dot{\sigma}$ isplacement' curve. Using a $\dot{\sigma}$ imensionless analog of Eqn (4.12), we obtain

$$\langle F_{\rm f} \rangle = \int_{S_N}^{S_E} \sin(2\pi S) \left[1 + \frac{2\pi}{K_{\rm e}} \cos(2\pi S) \right] \dot{\mathbf{d}} S$$

$$= -\frac{1}{2\pi} \left[\cos(2\pi S_E) - \cos(2\pi S_N) \right]$$

$$-\frac{1}{4K_{\rm e}} \left[\cos(4\pi S_E) - \cos(4\pi S_N) \right].$$

$$(4.15)$$

In accord ance with Eqn (4.15), the d imensionless d issipative friction force d ecreases from 1 as $K_e \rightarrow 0$ to 0 for $K_e > 2\pi$ when the whole cycle of movement is stable. The same conclusion follows from the analysis of the K_c and K_l d epend ences of the friction force (see Figs 5a,b in work [65]).

Thus, the friction force $\dot{\mathbf{d}}$ ecreases on increasing the contact and cantilever stiffnesses. However, this result is in contrad cantilever stiffnesses. However, this result is in contrad canter with the experimentally stated relation $F_{\rm f} \propto k_{\rm c}^2$ for the contact of a silicon nitrad probe and mice obtained in work [47] (see Section 4.1). Other experiments also show that the friction force increases with increasing contact stiffness. As was noted by the authors of work [65], it is possible that the lateral force has a constant component in $a^{\dot{\mathbf{d}}}$ ition to the sinusod al fluctuating component. In any case, this aspect of the problem remains unclear.

Kerssemakers and De Hosson in a number of works [48] proposet a phenomenological (geometric) theory of the SS effect. They introduced a so-called critical displacement amplitude ('stick parameter') of the form $\varepsilon_0 = F_{\text{max}}/k_{\text{c}}(\alpha)$, where $k_{\rm c}(\alpha)$ is the anisotropic lateral stiffness of the cantilever, and F_{max} is the maximum elastic force at the instant of the start of slip having a perior λ . In moving the probe over hexagonal layerer structures of NbSe₂ type, the region of lateral slip is bound by a circle of radius ε_0 and can bed ivit et into six areas which characterize thed irections of probable microslips corresponding to the strongest relaxation. Ultimately the path of the probe consists of a series of d eformational-relaxational isplacements taking place within the circle ε_0 . Base on this model the authors of Refs [48] connected the observed spasmed ic movement of the probe with contact anisotropy and expressed the quantity ε_0 in terms of the erivatives of the surface potential:

$$\varepsilon_0 = \frac{U'(\varepsilon_0)}{U''(\varepsilon_0)}$$

Using the lateral mot ulation mot e and this expression one can study the nonlinear characteristics of a tribocontact which are d epend ent on the form of the phase-interface potential relief. In the latest works [48], 'incomplete' microslips proving the existence of a lower threshold' of occurrence of the SS effect were also observed.

4.3 Using the molecular dynamics method

Some results relating to the application of the MD method have alread y been considered in Section 3. Below we would like, first, to analyze in more detail the evolution of the atomic structure of the 'probe-surface' contact which can be visualized in numerical simulation experiments and, second, to consider the mechanisms of energy defisipation in the process of probe slip over a surface accompanied by variations of normal and lateral forces.

In representative computer simulation experiments [69, 82-84, 94] giving an insight into the atomic structure of nanocontacts, two types of probe movement are const ered : along the normal to the surface of a sample (approaching and moving away) and lateral slip at a constant value of the normal force (or probe height). The upper layers of probe atoms are assumed to be stiff and ared isplaced in the normal or laterald irection with a step of the of er of 0.005 nm. The sample is mor eller by a finite set of parallel atomic planes (typically 10-20 planes) bount in the lateral plane by stiff walls; the lower surface is also assume to be stiff. In the case of 'sharp' probes, the total number of atoms is 10-100, and in the case of 'blunt' probes, it is about 1000. The number of surface atoms ranges from 100 to 10000. Oned imensional mot els are also consti eret. Following each step of load ing the contact along the normal or following lateral slip, the d ynamical relaxation of the coord inates and the velocities of the atoms of the sample and the probe is performed for some time on the expiry of which the system may be const $\vec{\mathbf{p}}$ ere $\vec{\mathbf{q}}$ as being in equilibrium, and its temperature reduces to a fixed value (usually close to zero) by multiplying all velocities by a corrective factor.

Figures 16a, b, c show the $\dot{\mathbf{c}}$ ifferent stages of load ing (a, b) and unload ing (c) obtained by simulation of the contact of a sharp Ni probe consisting of 10 planes with (111) orientation end ing with a single atom near its apex and a Cu (110) surface [69]. The projections of the positions of probe and surface atoms at $\dot{\mathbf{c}}$ ifferent instants of time are shown [sid e view (a, c), top view (b)]. Figures 16d, e show the $\dot{\mathbf{c}}$ epend ences of the normal forces on the probe $\dot{\mathbf{c}}$ isplacements d and u correspond ing to load ing ($\dot{\mathbf{c}}$) and unload ing (e).

When load ing the contact, the probe begins to move when the d istance between the apex and the surface is 0.4 nm. The instant at the beginning of the first sharp $\dot{\sigma}$ ecrease of the normal force (point J_1 in Fig. 16th) correspond s to land ing a Ni atom locater on the probe apex in the centre of a square former by Cu atoms (panel *1* in Fig. 16b). At d = 4.3 nm, 4 atoms of the probe (an apex atom and three upper ones) land in similar positions forming a commensurable (with the surface) structure (panel 2 in Fig. 16b). The force of attraction of the probe to the surface $F_{\rm N}(d)\dot{\mathbf{d}}$ ecreases quasilinearly on increasing d from 0.43 nm to 0.57 nm. At $d \approx 0.58$ nm, atomic layers at jacent to the contact area become d ison ered with the result that one layer of probe atoms d isappears' within the 'thickness' of the surface (d ipping' in it), and this is accompanied by a sharp decrease of the normal force (point J_2). The processes of atom exchange between the probe and the surface accompany each phase of increasing $F_{\rm N}(d)$, however, not all the sharp jumps of the normal force are connected with d ipping the atoms of the probe. As d is increase, the contact area grad ually grows in sizes including



Figure 16. Atomic structure and forces in the tribocontact of a 'sharp' Ni(111) probe with a Cu(110) surface. The structure of the contact at ind entation (load ing), she view (a) and top view (b), as well as at unload ing, she view (c), is shown. Panels in figures a-c correspond s tod ifferent phases of load ing (unload ing); at load ing, panels 1-8 correspond s tod isplacements d = 0.71, 0.72, 0.8, 0.87, 1.11, 1.15, 1.22 and 1.29 nm, and at unload ing, the start of unload ing correspond s to d = 1.01 nm, and panels 1-7 correspond tod isplacements u = 0.07, 0.21, 0.42, 0.56, 0.63, 0.77 and 1.05 nm. The change of the normal (d, e) and lateral (f) forces on the contact as a function of the stance is shown. Nikel and copper atoms are indicated by solid and open circles, respectively. (From work [69]).

1, 4, 8, 13, 15, 18, 23, ... atoms. On the whole, for 0 < d < 1 nm, the $F_N(d)$ force is attractive, exhibiting a multitur e of small variations connecter with the jumps of contacting atoms, since probe atoms, having a relatively small coord inating number, tend to d ecrease their energy forming a commensurate structure with the surface atoms. For d > 1 nm, the interaction of the probe with the sample as a whole takes on an attractive character, and the contact area begins to change its form (panels 5, 6 in Fig. 16b).

The evolution of the contact area in the unloading condition when the probe moves up from the surface is shown in Fig. 16c. The start of the reverse movement corresponds to a diepth of indientation d = 1.01 nm. The variation of the normal force with the displacement u is shown in Fig. 16e. The $F_N(u)$ diependience also diemonstrates the presence of spasmodic variations (see points U_1, U_2, \ldots), however, they are not as regular as at the loading movement. The formation of new atomic layers in the contact area is accompanied by a sharp diecrease of $F_N(u)$ at points U_1 , U_2 , ... In this case, before the formation of the layers, the structure of the contact brid ge becomes disordiered.

As was noted by many authors, the process of 'stretching' of the contact brid ge and the formation of new atomic layers

in this brd ge is accompanied by 'or d = -d is or d = -d is or d = -dtransitions affecting nanoscopic-scale regions. In the case being considered such a region counts for as few as several atoms in the cross section. At small u, the force $F_N(u)$ d ecreases with a large gradient, since the first structural change (point U_1) requires a const erable force. However, this point is intermed inte, and only after transition U_2 may an originating atomic layer be dentified. In periods of time between the formations of new layers, $F_N(u)$ increases quasilinearly corresponding to a quasi-elastic differentiation of the contact br $\dot{\mathbf{p}}$ ge. After transition U_5 the contact br $\dot{\mathbf{p}}$ ge makes up eight atomic layers und er the surface. Thed isruption of the one-atom contact (at u > 1 nm) correspond s to an unload ing force of about 1.5 nN. In the process of 'stretching' the contact brd ge, the structure of the contact area at jacent to the surface is commensurable with the Cu(110) structure, and the structure of the upper layers of the probe becomes hexagonal and commensurable with the Ni(111) surface.

The variation of the lateral force $F_L(s)$ for probe $\dot{\sigma}$ is placement s is shown in Fig. 16f. In this case the normal load ing force was 2.64 nN with a uniform $\dot{\sigma}$ is tribution between the atoms of the upper atomic layers of the probe. The sharp jumps of $F_L(s)$ correspond to the SS effect with a

 $\mathbf{\hat{d}}$ ouble period of about 0.35 nm being close to the lattice period s of Ni (0.352 nm) and Cu (0.361 nm). The points of structural transformations labelled T_i , M_i (i = 1, 2, ...) follow each other in the course of each slip period, and the work need of to overcome $F_L(s)$ increases from one period to another. This seems to be connected with increasing the d imensions of the contact brid ge, since, as follows from the results of computer simulation, after each slip phase the lower atomic layer of the probe is 'obliterated'.

The average value of the friction force in this numerical experiment was 2.06 nN. The process of probe movement is accompanied by transitions from an incommensurable (with the sample structure) structure of contacting layers to a commensurable one. These structural transformations occur d uring short period s of time. The slip generally starts at the interface between the Ni(111) and Ni(110) layers, where the last layer is commensurable with the Cu(110) structure. As was mentioned in Section 3.6, in metallic nanocontacts the variations of the normal force and the lateral force, are experimentally observed. Therefore the measurement of this conductivity can give valuable information on the atomic structure of contacts.

The authors of work [69] carrier out a simulation of nanoin entation and slip friction for a model of a blunt Ni probe of hemispherical form involving 1580 atoms, that approximately correspondent is to a radius of curvature of 4 nm, and Cu surface of 10 planes with (001) orientation involving 200 atoms (that is closer to the conditions of actual AFM experiments). The (001) orientation of the atomic layers of Ni is pseudiomorphous to the Cu(001) structure. In the process of lateral slip of the probe, a normal loading force of 9.1 and 12.9 nN was applied to it. As follows from simulation results, the average lateral force applied to the probe over several stick – slip cycles (Fig. 17) was close to 14 nN (under a loading 9.1 nN).

As follows from comparison of this $\dot{\sigma}$ ata (with consider eration for the value of the $\dot{\sigma}$ etachment force: -25 nN) and the JKR contact model, which is applicable to this case, a satisfactory agreement with this model may be obtained at $\gamma = 1.3$ J m⁻², $\tau = 3.7$ GPa. Thus, the value of the ad hesion work obtained is about twice as small as its macroscopic value for the contact of hard nickel with copper (about 2.8 J m⁻²). However, the shearing stress seems to be overestimated, since in this case the shear model ulus is equal to 17 GPa and, correspondingly, $G/\tau = 8.5$ rather than 29 (a characteristic value in macroconditions).

The structure of the contact area and the variation of the lateral force acting on the hemispherical Ni probe are shown in Fig. 17. Panels 1 and 2 correspond to normal forces of 9.1 nN and 12.9 nN, respectively. In the initial phase of probe slip (und er a load of 9.1 nN), the lower layer of probe atoms involving 24 atoms is in contact with the surface. The correspond ing contact area is relatively large and has a plane shape, therefore the character of slipd iffers from that considered in the case of a sharp probe. The SS effect now exhibits a period icity of about 0.15 nm, and the structural changes of the T_i or M_i types observed in the case of a sharp probe are not resolved.

Und er a load of 9.1 nN (panel *I*), the Ni surface 'sticks' to the Cu surface and the 'stiff' upper layers of the probe are $\dot{\sigma}$ isplaced relative to the lower ones. Below the interface surface linear $\dot{\sigma}$ islocations are seen. Panel 2 corresponds to the end of the slip phase. The structure of atomic layers



Figure 17. Atomic structure and forces in the tribocontact of a hemispherical nickel probe [1580 atoms, (011) orientation of layers] with a Cu(001) surface. Solid circles–Ni atoms, open circles–Cu atoms. (From work [69]).

becomes $\mathbf{\hat{\sigma}}$ iso $\mathbf{\hat{r}er}\mathbf{\hat{e}r}\mathbf{\hat{e}r}$, some atoms of nickel and copper exchange their sites, and the hemisphere shifts as a whole in the (100) $\mathbf{\hat{\sigma}}$ irection. After completion of the slip phase, the structure of the atomic layers is restored once the atoms of Ni shift to their new equilibrium position. Panels 3, 4 show similar contact structures (in the stick phase and after the slip phase) at a normal load of 12.9 nN. In this case the contact structures are more highly isod ered, and the SS effect is less regular.

It is also seen from Fig. 17 that the ratio of the static friction force $F_{\rm L}^{\rm S}$ to the average lateral force $\langle F_{\rm L} \rangle$ is roughly 2. In AFM experiments (see Fig. 3) this ratio is close to 1.5.

In works [82] the authors in their simulation experiments $\dot{\sigma}$ efine so-caller 'internal' and 'external' friction forces in such a way that the first of them is connecter with the increment of the total energy of a more elementary microslip (at the successive steps of simulation) and the second is considered as the increment of a remanent (after performing d'ynamical relaxation) lateral force acting on the probe after each step. It is the author's opinion that such a d'efinition of the friction forces d'oes not ad equately take into account their d'issipative nature, since the corresponding contributions contain a high portion of conservative forces. Without

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constitution), we must obtain near-zero friction forces, if a microslip correspond s to one lattice period of a surface structure. This follows from the thentity of atom configurations, if the effects of atom mixing are not taken into account. The authors of works [82] actually believe that the kinetic energy of a probe is thermalized in a contact area involving a limited number of probe and surface atoms. In this case continuous local heating of the system takes place, whereas in the real situation the thermal energy must go out into the volumes of the contacting bod ies. As to work [69], the authors d on take into account losses connected with heating the tribocontact, and the integration of the lateral force over the slip period may result in a contribution of conservative forces having nothing to d o with friction.

Summing up the results of the last three sections, one can state that the numerical MD experiments allow one to create a realistic physical picture of the evolution of an atomic structure in the 'probe-surface' contact area for loading, unload ing and the lateral movement of a probe, however, the problem of the practical calculation and prediction of the friction forces und er the condition of AFM experiments still remain to be solver. Using the contact-mechanics approximation, one can (at least for elastic contacts) calculate the at hesive friction forces, but attempts to reflect correctly the role of the atomic structure do not meet with success. Moreover, the empirical parameters of the theory may be grossly changer when going to an atomic scale. As to the simple mot els constit erei in Section 4.2, they provit e a convenient way of more elling surface images observer in AFM, but also do not allow one to obtain a detailed quantitatived escription of friction forces.

4.4 Theory of adhesive friction

The basic \$\vec{p}\$ eas of this theory were cons\$\vec{p}\$ ere^1 in work [75]. The corresponding mechanism is illustrated in Fig. 18. Initially the probe is located at a position corresponding to the minimum energy of a tribosystem. Ind ivid ual lines connecting the atoms of the probe and the surface in Fig. 18a correspond to established at hesive bond s. If the lateral force applier to the probe exceers the critical value of the friction force at rest, then ad rastic microslip occurs, being catastrophic in character, and the probe is d isplaced over a $\dot{\sigma}$ istance Δx in the lateral $\dot{\sigma}$ irection. Since this $\dot{\sigma}$ isplacement takes place in a very short time interval (probably about 10^{-12} s), the at hesive bond s have no time to relax and therefore, on the one hand, the abrupt breaking of o^{ab} bond s, and on the other, the avalanche-like making of new bond s (corresponding to a finite position of the probe) occur (Fig. 18b). As a result the atoms of the surface and the probe come into oscillatory motion whose energy eventually transforms into heat. This argumentation is close to \$\vec{p}\$ eas arguer in the work by Teibor [28]. The fourth ations of this theory can be concretizer as follows:

a) the amount of energy $\mathbf{\hat{\sigma}}$ is signated into heat in one microslip is $\mathbf{\hat{\sigma}}$ etermined by the sum of the absolute changes of the energy of ind iver ual at hesive bond s (Δw_k correspond s to k-th at hesive pair):

$$\Delta W = \sum_{k} |\Delta w_k|; \qquad (4.16)$$

b) an elementary microslip has a length of the of $\dot{\mathbf{r}}$ er of the lattice perior, $\Delta x = d$;



Figure 18. Mechanism of energy $\hat{\sigma}$ issipation with $a\hat{\sigma}$ hesive friction. (a) Probe is located at a position corresponding to the minimum of the energy of the 'probe-surface' system. Sold lines show ind ivid ual at hesive bord s between the atoms of the probe and the surface. The contact area is shown in a simplified form without constit ering d eformation. The atoms of the surface making these at hesive bord s are at inequilibrium positions relative to those at d istances well away from the contact area. (b) New equilibrium position of the probe after a sud en microslip over a surface structure period . 'Of d' at hesive bord s have no time to relax. They are shown by thin lines, and newly formed bord s are shown by sold lines. Atoms on both of these bord s come to oscillatory motion, and their excess energy goes into heat via the phonon subsystem. The friction force is the ratio of the total bord -breaking energy to the d isplacement of the probe.

c) the friction force is equal to

$$F = \frac{\Delta W}{\Delta x} \,. \tag{4.17}$$

The first calculations in the framework of this scheme [75] were performed for a simplified case without const ering the d eformation of the contact area and the relaxation of the atomic structure. Silicon – silicon and W (probe) – (100) α -Fe contacts were constructed. The dependence of the normal force applied to the contacts on the height h and the radius of the probe has a power form $(F \propto h^{-3.5})$ and a near-linear form, respectively, that is in good agreement with experimental results [35]. The calculater 'friction-load' curve is similar to that obtained in work [35] for Si-NbSe₂ contacts. In works [66] this mot el was generalizer with construction for the d eformation of the contact area given by a mod el function. The parameters of this function were d etermined from the condition for the minimum of the tribosystem energy which includes the 'probe-sample' interaction and the $\dot{\mathbf{\sigma}}$ eformation energy of the bond s for the sample. It is assumer that the probe is stiff and retains the atomic structure of the initial material. Fig. 19 shows the results of calculation of the d epend ences of the friction forces on the load ing force and the radius of a parabolic probe for the diamond graphite' system. The corresponding curves are plotted with (Fig. 19a) or without (Fig. 19b) const ering the d eformation of the contact area. It makes sense to compare these theoretical $\dot{\mathbf{q}}$ eper $\dot{\mathbf{q}}$ encies with the results of experiments [35, 43, 72], in which the 'friction force-load ing force' curves were obtained for the following contacts: Si (probe)-NbSe₂



Figure 19. Mot el theoreticald eperd ences of the at hesive friction force for a stiffd iamon' probe on the (0001) graphite surface on the load ing force and the rad ius of the probe: with (a) and without (b)d eformation of the contact area. Sold curves are plotter for the sake of convenience. (From work [66])

(the rat ii of curvature of the probes are 12 and 48 nm); d iamond (probe)-tungsten carbd e (with a rad ius of curvature of 110 nm) and Pt (probe)-mica (with a radius of curvature of 140 nm).

Correlating the d epend encies presented in these works with Fig. 19a, one can note the same irregular character of experimental points at small loading forces. In this case the irregularities are more pronounce at small rat ii of the probe when the d iscreteness of the atomic structure manifests itself more clearly. It should be noted that without considering the $\dot{\mathbf{d}}$ eformation of the contact area, the theoretical 'friction-load' d epend ences are smooth and resemble the run of similar curves for the contact-mechanics mot els (see Fig.19). The results of calculation [66] at R = 10 nm an the d at a for Si – NbSe₂ [35] at R = 12 nm are in qualitative agreement, whereas in a quantitative sense the theoretical values of friction forces are two-three times larger. This d istinction may be connected with the presence of d ifferent types of interacting atoms and, correspondingly, with the ifference in the force characteristics of tribosystems as well as with the inaccuracy of formula (4.17) and /or experimental errors.

the ratius of curvature of the probe is supported by experimental d ata [35, 43]. Ind ed , for the Pt-mica contact (R = 140 nm) [43] the friction forces are an of \vec{r} er higher than those in the case of the Si-NbSe₂ contact (R = 12nm). As was mentioned in Section 4.1, in experiments [72] one obtained anomalously low values of friction forces at a large probe ratius (110 nm) as well as too low (for such a stiff contact) a value of the shearing stress (238 MPa), calculater in the DMT approximation. It is likely that the ratius of curvature of an outward -projecting part was about 10 nm. As was mentioned at the end of Section 3.1, the ad hesive

mot el gives a qualitative picture of the atomic perior icity of the SS effect. The d etailed quantitative calculations of lateral forces as well as the investigation of the energy threshold for occurrence of slip still remain to bed one. The success of the phenomenological approach user in work [48] (See Section 3.1) also counts in favour of the key role of geometry in occurring the SS effect. The period icity of normal forces and the inversion of normal force contrastor epending on the ratio a/d (a is the ratio is of a nanowire) were obtained in calculations of the interaction of single and multilayer nanowires with a surface [53].

A theory outliner in work [75] lears to a new (macroscopic) relation between the shearing stress (the shear mot ulus) and the surface energy of sold s (see Fig. 6). In the case of a plane contact of two both ies with an area A, the at hesion energy is $W = \gamma A$, where γ is the at hesion work ở eterminer by formula (3.2). In a sước en microslip over the $\dot{\mathbf{d}}$ istance d such energy goes into the breaking and making of new at hesive bond s, that is, d issipates into heat. Therefore the friction force is

$$F = \frac{\gamma A}{d} . \tag{4.18}$$

Taking into account formulas (4.18) and (2.5), we obtain for the at hesive friction force

$$\tau = \frac{\gamma}{d} \,. \tag{4.19}$$

For the contact of homogeneous materials, with const eration for expression (3.2) and relation $\gamma_{12} = 0$, formula (4.19) takes the form $\tau = 2\sigma/d$, where σ is the specific surface energy. In aid ition, by virtue of the proportionality between the macroscopic shear mot ulus G and the shearing stress τ , the last result can be transformed into an equivalent form $Gr \propto \sigma$, where r = d/2 is the atom ratio ius. Figure 6 supports the conclusion that this correlation in fact hold s.

4.5 Dynamical friction forces

When a probe moves with a velocity V over the surface of a sample, the energy of its onward movement can d issipate through ynamical mechanisms giving no contribution to the friction force in the static case. Among the most important mechanisms of this type are the fluctuation-electromagnetic interaction as well as the processes of excitations of electrons and phonons [8, 9]. We willd ifferentiate fluctuation-electromagnetic and electron processes, assigning to the latter the effects which are determined by the short-range excitations of electron plasma and by the formation of electron-hole pairs, whereas the fluctuation-electromagnetic interaction will be const ere as a long-range effect taking place in the case when a probe and a surface are separated by a vacuum interlayer. This viewpoint iffers from the interpretation use in a recent paper by Tomassone and Wit om [107] who considered electron processes in a wider sense combining them with fluctuation-electromagnetic ones.

Without question a self-consistent quantum theory must take into account all possible types of excitations in a unifier way, however, at the present time it is still in the initial stage of $\dot{\sigma}$ evelopment. In any case the specification of $in\dot{\sigma}$ iv $\dot{\sigma}$ ual mechanisms is essential for a more fund amental und erstand ing.

It shouk be noted that a typical scan velocities in an AFM are much less than the sound velocity and the Fermi velocity of electrons, therefore, in the absence of amping of phonon and plasmon modes, the processes of one-particle excitations are forbided en by the law of conservation of energymomentum. For example, the generation of single acoustic phonons by a moving atom (probe) is possible for $V > V_s$ (where V_s is the sound velocity). In this case phonons are emitted within the Cherenkov cone $\cos \theta = V_s/V$. With finite d amping, particles may loss their energy by excitation of quasi-particles at arbitrarily small velocities.

As was mentioned in Section 4.4, elementary excitations always accompany the finite stages of tribosystem-energy $\dot{\mathbf{d}}$ issipation in stick-slip processes, that is, in the contact mode of an AFM, but in this case we mean only d issipative (viscous) velocity-proportional forces acting between the probe and the surface which can be const ered as relatively weak. In ed , in the case of the contact mote, the total work performed by these forces (if we use an estimate on the basis of subsequent analysis) $\dot{\sigma}$ oes not excest 1 pH × 2 × 10⁻¹⁰ m = 2 × 10⁻²² J, whereas the at hesive friction forces are three-four of ers of magnitude larger. However, this estimate is based on an average value of the probe velocity of 1 m s⁻¹ and if a microslip takes place in a time of 10^{-12} s, this value should be increased by two of ers of magnitude, and then the viscous force may be comparable with the static friction force. In any case d'ynamical friction has to play a large role in quartz crystal microbalance and SFA experiments and in the mot ulation mot e of AFM.

Fluctuation-electromagnetic friction forces. Despite the simplicity of the main $\dot{\mathbf{r}}$ ea (a moving fluctuating $\dot{\mathbf{\sigma}}$ ipole in $\dot{\mathbf{r}}$ uces surface electrical currents, whose Joule $\dot{\mathbf{\sigma}}$ amping is the final result of friction), so far, when calculating the corresponding forces, there is no clarity in respect to a number of main factors, such as the $\dot{\mathbf{\sigma}}$ ependiences of these forces on the velocity, $\dot{\mathbf{\sigma}}$ istance, temperature and so on (see, for example, works [9, 108–112] and references in these works). It is the author's opinion that the most common approach to the solution of this problem is given by the Lifshitz fluctuation-electromagnetic theory, therefore we use below the results obtained in the framework of this theory [108–110].

Assuming that a neutral atom having a velocity V moves parallel to a surface on a^{$\dot{\sigma}$} istance z from it (z exces^{$\dot{\sigma}$} s typical atomic sizes), for the lateral (friction) force acting on this atom (in the linear approximation with respect to the velocity) one can write

$$F = -\frac{3\hbar V}{8\pi z^5} \int_0^\infty \dot{\mathbf{d}} \,\omega \left\{ 2 \left[\alpha''(\omega) \frac{\dot{\mathbf{d}} \,\Delta''(\omega)}{\dot{\mathbf{d}} \,\omega} - \Delta''(\omega) \frac{\dot{\mathbf{d}} \,\alpha''(\omega)}{\dot{\mathbf{d}} \,\omega} \right] \right. \\ \left. + \omega \left[\alpha''(\omega) \frac{\dot{\mathbf{d}} \,^2 \Delta''(\omega)}{\dot{\mathbf{d}} \,\omega^2} - \Delta''(\omega) \frac{\dot{\mathbf{d}} \,^2 \alpha''(\omega)}{\dot{\mathbf{d}} \,\omega^2} \right] \right\} \coth\left(\frac{\omega\hbar}{2k_{\rm B}T}\right)$$

$$(4.20)$$

where $\alpha(\omega)$ is the atomic polarizability, $\Delta(\omega) = [\varepsilon(\omega) - 1]/[\varepsilon(\omega) + 1]$, $\varepsilon(\omega)$ is the d ielectric function of the med ium, and k_B , \hbar and T are the Boltzmann contact, Planck constant and the temperature, respectively. The quantities with two primes correspond to the imaginary parts of the correspond ing functions. For the normal (to the surface) movement of a neutral particle, a formula similar to Eqn (4.20) is not available.

It follows from formula (4.20) that at T = 0 the friction force $\dot{\mathbf{c}}$ oes not equal zero, which is a physical result of the existence of zero fluctuations of an electromagnetic fielt in the substance. At T = 0, formula (4.20) can be transformed into the simple-form user in work [75]:

$$F = -\frac{3\hbar V}{4\pi z^5} \int_0^\infty \dot{\mathbf{d}} \,\omega \alpha''(\omega) \frac{\dot{\mathbf{d}} \,\Delta''(\omega)}{\dot{\mathbf{d}} \,\omega} \,. \tag{4.21}$$

Assume that the strongest line in the absorption spectrum of an atom has a frequency ω_0 . Then, assuming the $\dot{\sigma}$ amping coefficient to be zero, for the imaginary part of polarizability we obtain

$$\alpha''(\omega) = \frac{\pi e^2 f_0}{2m\omega_0} \delta(\omega - \omega_0), \qquad (4.22)$$

where e, m, f_0 are the electron charge, the electron mass and the oscillator strength, respectively. Using the stand and Lorentz-Drud e mod el approximation for the d ielectric function of metal and substituting Eqn (4.21) in Eqn (4.22), we obtain [110]

$$F = \frac{3\hbar e^2 f_0 \tau^2 V}{4mz^5} \frac{y^2 (12x^4 - 4x^2y^2 + 4x^2 - y^4)}{x(4x^4 - 4x^2y^2 + 4x^2 + y^4)^2}, \qquad (4.23)$$

where $x = \omega_0 \tau$, $y = \omega_p \tau$, ω_p and τ are the plasma frequency and the relaxation time of metal electrons, respectively. The analysis of formula (4.23) shows that the sign of $F^{\dot{\alpha}}$ epends s on the relation between the absorption frequency of an atom and the plasma frequency. The force is braking for $\omega_p \ge \sqrt{2}\omega_0$. For metals, typical values of parameters $\tau a \mathbf{n}^{\dagger} \omega_{p}$ are about $10^{-14} - 10^{-15}$ s and 5 - 10 eV, respectively. In this case the above cont ition is fulfillet, however, for the high-frequency lines of atomic absorption, the opposite situation is possible, and the lateral force may become accelerating. However, it shout be noted that the absolute values of the spectra-overlap integral d etermined by the x, y d epend ent factor in formula (4.23) d ecrease with increasing ω_0 , therefore, to estimate correctly the total force F, it is necessary to take into account in d etail the absorption spectrum of the atom in a narrow frequency region near $\omega_p/\sqrt{2}$. Calculations show that for a typical QCM experiment [21, 22] in the case of at sorption of a krypton atom on gold, the value of the spectra-overlap integral, being d etermined by the x, y d epend ent factor in formula (4.23), is close to -0.1. Then at z = 0.04 nm the motion \dot{d} amping time is $\Delta t = MV/F = 0.6$ ns (M is the mass of a krypton atom), which is close to the experimental value.

In the $d\hat{d}$ itive approximation [108, 109], the lateral friction force acting on a moving parabolic probe with a $d\hat{d}$ istance *h* between the apex and the surface can be obtained from formula (4.20). Expressing $\alpha(\omega)$ via the $d\hat{d}$ ielectric function of probe material $\varepsilon_1(\omega)$ with the use of the Clausius-Mossotti formula and integrating over the volume of the probe, we obtain

$$F = -\frac{3}{64\pi} \frac{\hbar R V}{h^3} J(\varepsilon_1(\omega), \varepsilon(\omega)), \qquad (4.24)$$

where *R* is the ratios of curvature of the probe, and the frequency integral $J(\varepsilon_1(\omega), \varepsilon(\omega))$ coincides with that in formula (4.20) with replacing atomic polarizability by $\widetilde{\Delta}''(\omega) = \text{Im}\{[\varepsilon_1(\omega) - 1]/[\varepsilon_1(\omega) + 2]\}.$

As follows from formula (4.24), the temperature $\dot{\sigma}$ epen- $\dot{\sigma}$ ence of the friction force becomes essential for $\omega \hbar \leq 2k_{\rm B}T$, when $\coth x \to x^{-1}$. At room temperatures $2k_{\rm B}T \approx 0.05$ eV, therefore, the processes of low-frequency absorption, such as $\dot{\sigma}$ ipole relaxation (in $\dot{\sigma}$ ielectrics) and infrare absorption in ionic and conducting crystals, contribute predominantly to the friction force.

The numerical estimates of the friction force from formula (4.24) performet for d ifferent combinations of materials show that for typical probes with R = 10-20 nm, at V = 1m s⁻¹, z = 0.2 - 0.3 nm and at room temperatures the values obtainer fall in the range 0.1 to 10 pN. Such forces can materially contribute to the camping coefficients of the lateral oscillation of AFM cantilevers, if these latter have O of the of $10^4 - 10^5$. The Q-value related to the d ynamic friction force can be estimated with the use of the following formula: $Q = k_l V / 2\Omega_l F$, where k_l is the stiffness $\dot{\mathbf{c}}$ efine $\dot{\mathbf{b}}$ y formula (2.2) and the frequency Ω_l is likely to be an order higher than the normal-oscillation frequency [see expression (2.3)]. For stiffness 100 N m⁻¹, frequency 10^6-10^7 Hz, velocity 1 m s⁻¹ and force 1-10 pN, one obtains $Q = 5 \times 10^5 - 5 \times 10^7$, therefore, the measurement of the Qshift resulting from an electromagnetic link between a probe and a surface is a real experimental task.

Electron friction. The mechanism of electron friction d ue to the generation of electron-hole pairs was first analyzed by Persson (see references in work [89]) in connection with the problem of amping the lateral oscillation of films a sorbe on a metallic substrate. An interrelation between the friction force resulting from the scattering of conduction electrons by oscillating a sorbate atoms and the change of resistance of a metal was user . Designate the inverse d amping time of the lateral oscillation of an a sorbate atom as $1/\tau_A$, then the à ynamic equation for conduction electrons will include an ation itional contribution to the friction force equal to $Mn_A V/mnd\tau_A$, where M is the mass of a surface atom and $n_{\rm A}$ is the surfaced ensity of atoms in a film, m, n and d are the mass of the film, the d ensity of cord uction electrons and the film thickness, respectively. The velocity-proportional coefficient can be considered as the inverse relaxation timed ue to an aid itional mechanism of electron scattering, $1/\tau_e$. As a result, resistivity is increased by a factor of $\Delta \rho = m/ne^2 \tau_e = Mn_A/n^2 e^2 \tau_A$, and the required d amping time τ_A is

$$\tau_{\rm A} = \frac{Mn_{\rm A}}{n^2 e^2 d\Delta\rho} \,. \tag{4.25}$$

This theory gives an a^{\dagger} equate estimate of the lateral-motion \dot{a} amping time for molecules in the case of physical an^{\dagger} chemical a^{\dagger} sorption, however, it is too simple $an^{\dagger} \dot{a}$ oes not take into account the structure of the film an^{\dagger} the character of the electron \dot{a} istribution near the film surface.

In work [113], an expression for the braking losses of a hydrogen atom by excitation of the electrons of metal was obtained on the basis of the quantum perturbation theory. Conduction electrons were considered in the 'jelly' model with a sharp jump of potential at the bound ary. On the assumption that for heavy atoms of mass M the braking force

remains the same, one obtains the following formula for the lateral motion d amping time:

$$\Delta t = \frac{MV}{F} = \frac{2\pi M}{27\hbar a_{\rm B}^2 k_{\rm F}^4} \,, \tag{4.26}$$

where $k_{\rm F}$ is the Fermi vector of the electrons of metal, $a_{\rm B}$ is the Bohr rat ius. Assuming that $k_{\rm F} = 10^8$ cm⁻¹ and $M = 1.4 \times 10^{-25}$ kg (krypton), one obtains $\Delta t = 1.1 \times 10^{-11}$ s. This value is two of ers of magnitud e less than experimental values. Two factors, however, must result in an add itional d ecrease of Δt : first, for atoms with a large nuclear charge, the losses of energy must be larger, since the effective charge of heavy atoms is greater than unity; second, for films with a regular period ic structure, Δt d ecreases N times (N is the number of atoms in a film [114]). Thus, the theory being const ered gives too large values for the electron friction force and small values for the motion amping time for ad sorbed films.

Another approach to the problem of electron friction was proposet in work [75]. The corresponding mechanism is base on a phenomenological theory of braking losses of slow ions in sold s (see references in work [75]): the losses of energy result from a hypothetic exchange of electrons belonging to a moving atom, on the one hand, and to an atom of the target, on the other (in the case of AFM, an exchange of atoms takes place between the probe and the surface). Each electron of the probe passing through the equipotential surface of the 'probe-surface' system loses the relative-movement momentum mV. In fact, this argumentation is close to the Persson mot el relating the braking force with the process of electron scattering. In accord ance with this theory, the loss of energy of a neutral atom with nuclear charge Z_1 and velocity V flying at a sighting istance b from a surface atom with nuclear charge Z_2 is

$$\Delta E = -\frac{me^2}{\hbar} \frac{0.35(Z_1 + Z_2)^{5/3}}{\left[1 + 0.16(Z_1 + Z_2)^{1/3}b/a_{\rm B}\right]^5} V.$$
(4.27)

Assuming that the sample has a uniform d istribution of atoms with ad ensity *n* and the moving atom is ad istance *z* from the surface, upon integration of formula (4.27) over all possible sighting parameters, we find

$$\frac{\dot{\mathbf{d}} E}{\dot{\mathbf{d}} x} = F(z) = -0.7(Z_1 + Z_2)^{5/3} \frac{me^2}{\hbar} nV \\ \times \int_z^\infty \frac{b \arccos(z/b) \dot{\mathbf{d}} b}{\left[1 + 0.16(Z_1 + Z_2)^{1/3} b/a_{\mathbf{B}}\right]^5}.$$
(4.28)

For a Kr atom on the gold surface formula (4.28) gives $F(z) = 1.7 \times 10^{-16} z^{-2.4} V \text{ nN}$ (z is measured in angstroms, V in m s⁻¹), hence it follows that the d amping time at z = 0.35 nm approximates 1ns, in good agreement with experiment.

From this theory one can also easily obtain a braking force acting on an AFM probe with the use of the 'jelly' $m\sigma^{\dagger}$ el and the locally-plane approximation for the electron istribution within a uniform metallic contact form σ^{\dagger} by a parabolic probe with a rat ius of curvature *R* and a plane surface [75]:

$$F \approx -\frac{3\pi}{10} (3\pi^2)^{1/3} \hbar V n_{\rm e}^{4/3} \frac{(R+h/2)^2}{b^2 R^2} (1+bR) \exp(-bh) ,$$
(4.29)

where *h* is the $\dot{\mathbf{d}}$ istance of the probe apex from the surface, and n_e is the electron $\dot{\mathbf{d}}$ ensity in metal. In the case of the Al–Al contact $b \approx 1.19 \text{ nm}^{-1}$, then at R = 20 nm, h = 0.2 nm, $V = 1 \text{ m s}^{-1}$ from formula (4.29) one obtains $F \approx 0.67 \text{ pN}$. In the case of the contact of noncond ucting bod is, the role of this mechanism is likely to be insignificant.

Phonon friction. There is also no commonly accepter viewpoint regaring ingrigation phonon friction. This is connecter to some extent with the fact that the corresponding mechanism manifests itself on the background of structural effects, whose role was mentioned above and which may be induced by the mechanism of the breaking of at hesive bord s.

Sokoloff, using the perturbation theory, obtained the following formula for the braking force of a single a^{\dagger} sorbed atom in a film [114]:

$$F = \frac{1}{M} \sum_{\mathbf{k}} \frac{\gamma k_x^2 |f(\mathbf{k})|^2 V}{\left[\Omega_0(\mathbf{k})^2 - k_x^2 V^2\right]^2 + \gamma^2 k_x^2 V^2},$$
 (4.30)

where $\Omega_0(\mathbf{k})$ is the phonon frequency, γ is the inverse $\dot{\mathbf{k}}$ amping time, k_x is the projection of the phonon wave vector \mathbf{k} onto the $\dot{\mathbf{k}}$ irection of movement, $V \operatorname{ar} \dot{\mathbf{k}} M$ are the velocity $\operatorname{ar} \dot{\mathbf{k}}$ mass of the atom, respectively, $\operatorname{ar} \dot{\mathbf{k}} f(\mathbf{k})$ is the two $\dot{\mathbf{k}}$ immensional Fourier transform of the force of interaction with the surface. For a perior ic force, $f(\mathbf{k})$ is proportional to $\delta_{\mathbf{k},\mathbf{G}}$, where \mathbf{G} is the two $\dot{\mathbf{k}}$ immensional vector of the reciprocal lattice. In the limit $\gamma \to 0$ formula (4.13) ref uces to

$$F = \frac{\pi}{M} \sum_{\mathbf{k}} k_x |f(\mathbf{k})|^2 \delta \left(\Omega_0^2(\mathbf{k}) - k_x^2 V^2 \right).$$
(4.31)

As is seen from formula (4.31), equality $\Omega_0(\mathbf{k}) = k_x V$ $\dot{\mathbf{d}}$ etermines the cord ition for phonon generation and cannot obviously be fulfilled at velocities lesser than the sourd velocity. However, at $\gamma \neq 0$, the more general formula (4.30) gives a finite friction force, though its value must be small, being proportional to $\gamma V/\Omega_0^4(\mathbf{G})$ (at $V \to 0$). To obtain a realistic (for QCM experiments) estimate of the braking time of an d sorbed film forming a structure incommensurable with d sorbed film forming a structure as being partially d isole ered, that violates its translational symmetry and contributes significantly to friction, or uses the overestimated phonon d amping time (10⁻³ s). In the latter case from formula (4.31) follows

$$F = -\frac{\pi^2 N}{GMV_s^2} \left| f(\mathbf{G}) \right|^2,$$

where N is the number of atoms in the film, V_s is the sound velocity, and G is the minimum vector of the reciprocal lattice. In this case, as we have seen, the friction force $\dot{\sigma}$ oes not $\dot{\sigma}$ epend on the velocity. Obviously, its valued epend s to a large $\dot{\sigma}$ egree on poorly known parameters N, V_s , f(G), therefore, estimation of the role of this mechanism requires and itional analysis. It is known, for example, that the phonon velocity in small-size films is closer to 100 m s⁻¹ rather than to 1000 m s⁻¹ (the value used in work [114]). On the other hand, the value of the Fourier-factor f(G) must be essentially epend ent on the $\dot{\sigma}$ istance z between the film and the surface, $\dot{\sigma}$ ecreasing with increasing z.

Dynamic phonon friction, however, also arises in motion of in ivit ual atoms as well as AFM probes. Estimates of the correspond ing forces may be made in the framework of the quantum perturbation theory [115]. In this case the processes of scattering of surface phonons are of primary importance. For the high-temperature acoustic spectrum of phonons corresponding to temperature T and condition $V/V_s \ll 1$, the friction force turns out to be

$$F \approx -\frac{S(k_{\rm B}T)^2}{\left(\hbar V_{\rm s}\right)^3} \left| U_{\rm G}(z) \right|^2 \frac{V}{V_{\rm s}} , \qquad (4.32)$$

where $U_{\mathbf{G}}(z)$ is the two $\dot{\mathbf{\sigma}}$ imensional Fourier-factor of the atom-surface interaction potential, and S is the area of the unit cell. The $z\dot{\mathbf{\sigma}}$ epend ence of the friction force is determined by the concrete form of the Fourier-factor $U_{\mathbf{G}}(z)$, and the quad ratic temperatured epend ence is determined by the twod imensional nature of the phonon spectrum of the surface.

Figure 20 illustrates the $\Delta t(z)$ $\dot{\mathbf{c}}$ eper $\mathbf{\hat{r}}$ ence for braking a krypton atom on the silicon (111) surface [115] obtaine $\dot{\mathbf{r}}$ on the basis of formula (4.32) at $\dot{\mathbf{c}}$ ifferent temperatures. In calculations an interatomic potential of the form $V(r) = -C_6 r^{-6} [1 - 0.5(r_0/r)^6]$ with parameters $C_6 = 3.75 \times 10^{-78}$ J m⁶, $r_0 = 0.38$ nm was use $\dot{\mathbf{r}}$. Fig. 20 shows that the phonon mechanism may provide the braking time of 1ns observed in QCM experiments, if the atom is a sorbed at a realistic istance of 0.3 - 0.35 nN from the surface.



Figure 20. Theoretical $\hat{\mathbf{c}}$ eperf ence of the braking time for a krypton atom $\hat{\mathbf{a}}$ sorber on a Si(111) surface on the $\hat{\mathbf{c}}$ istance from the surface $\hat{\mathbf{ar}}$ the temperature. Phonon mechanism of friction. (From work [115].)

In work [75] the problem of phonon friction was consti[†] eret[†] in connection with braking an AFM probe. In the acceptet[†] mot[†] el the presence of a vacuum interlayer (of atomicd[†] imensions) between the probe and[†] sampled[†] oes not impet[†] e the passage of phonons transferring momentum and[†] is taken into account through the change of the sound[†] velocity. Then, in the Debye (low-temperature) approximation, the friction force acting on a probe with rad[†] is *R* is

$$F = -\frac{\pi^3}{45} \left(\frac{k_{\rm B}T}{V_{\rm s}\hbar}\right)^4 R^2 \hbar V \frac{V_{\rm t}}{V_{\rm s}}, \qquad (4.33)$$

where V_t and V_s are the sound velocities for the tribocontact and in the volumes of bodies, respectively. At R = 20 nm, V = 1 m s⁻¹, $V_s = 6600$ m s⁻¹ (silicon), $V_t/V_s \approx 0.1-0.01$, T = 300 K, the estimate of the friction force gives F = 0.5-5 pN. This value is comparable with values d etermined by other mechanisms of ynamic friction. Stoneham, however, called attention to the d rawback of this approach, in which contacting bot ies are considered as phonon reservoirs [116].

4.6 Other theories

Closing the review of theoretical \mathbf{mot} els, we will briefly touch on some other \mathbf{mot} els of nanostructural friction.

Persson [117] stuf ist the mechanism of lubrication friction for the purpose of interpreting experiments performs with the use of an SFA. It was assume that tangential stress applising to the interface layer of molecules sand wich is between the plates of the SFA is a function of the slip velocity: $\sigma = \sigma(V)$. This relation was supported by numerical experiments. It was also postulated that the at sorbed film may be in the solid or liquid state, alternately 'oscillating' between these states d'uring the motion of the upper plate in the stick – slip regime, and the thermod ynamics of the correspond ing phase transition are characterized by a phased iagram in the variables temperature – d egree of coating.

If the film is in the liquid phase, the slip velocity of the upper plate of the SFA may bed istinct from zero at arbitrarily small values of the shearing stress. If the film congeals, then $\sigma \neq 0$ and V = 0. Thus, the lack of sticking is connected with the formation of a two d imensional liquid interlayer. This agrees with experiment. If the film is in the sold phase and has a structure commensurable with that of the substrate, this structure retains until σ reaches a critical value σ_0 at which the film transforms into the liquid phase. However, ond ecreasing σd own to values less than σ_0 , friction remains low until the shearing stress reaches some new critical value at which the film congeals again. Thus, this mod el explains the hysteresis of friction forces observed in the SFA experiments.

Sokoloff [64] \dot{a} iscusse the continuous of isappearance of friction in finite-size systems using a dynamic model of an isolated atomic chain. Since the phonon modes of a finite-size solf body are separated from each other by a relatively with e interval, it may occur that the distance between these modes exceed s a natural linewith the In this case the transformation of a translational motion into vibration modes (and eventually into the thermal energy) is hampered and this motion may continue without losses for a long time. For a three-dimensional cubiform sample, in the acoustic limit the corresponding condition has the following form (Na = L is the cubed imension, *a* is the lattice constant) [64]

$$\frac{\left(V_{\rm s}\pi/Na\right)^2}{\omega} \gg \gamma$$

Then at $V_s = 10^5$ m s⁻¹, L = 1 cm this condition gives $\gamma \omega \ll 10^{11}$ s⁻² that can be valid for low-frequency acoustic modes.

Using the method of inelastic scattering of molecular helium beams, the authors of work [118] measured the oscillatory-motion amping constants (for motion along the normal to the surface) for molecules of typical lubricating materials (octane and hyd rocarbons) on a iamond (111), lead (111), ruthenium (001) and copper (111) substrates. In the farinfrared region (< 15 MeV), the measured a amping constants were found to be 0.2-1.1 MeV. Hence, in this case we obtain an estimate $\omega\gamma = 10^{24} - 10^{25}$ s⁻². The half-widt th of absorption lines turned out to be in good agreement with the theoretical formula

$$\gamma = \frac{M\omega_0^2}{A\rho V_{\rm s}} \,,$$

where M is the mass of a^{\dagger} sorbate, ω_0 is the oscillation frequency, A is the surface space occupiet by a^{\dagger} sorbate, ρ and V_s are the mass \dot{a} ensity of the substrate and the velocity of transverse phonons, respectively. The results of work [118] show that the \dot{a} amping of the translation motion of molecules in the \dot{a} irrection of the surface normal are a^{\dagger} equately explained by the phonon mechanism, if: first, the frequency of the oscillation of molecules is much less than the frequency of volume phonon mod es; second, even weak chemical interactions capable of lead ing to the occurrence of a \dot{a} ominating contribution of electron excitations are absent.

Persson [119] proposet a new theory of the friction of rubber (polymer) on a solir surface. Accord ing to this theory the greatest contribution to the friction force is from internal friction $\vec{\sigma}$ etermined by the fluctuation character of surface stresses acting on the rubber from the microrid ges of a solir surface.

Another contribution is connected with the a^{\dagger} hesive force. At low slip velocities, the a^{\dagger} hesive forces d^{\dagger} eform the surface of rubber in such a way that it fills the valleys of the surface relief. At very low velocities, the first mechanism is d^{\dagger} ominant, since most polymer materials exhibit cons d^{\dagger} erable internal friction even at very low frequencies (of the odd er of 0.1 s^{-1}).

The main conclusions and problems of a theoretical nature to emerge from Section 4 can be summarized as follows:

On the whole, the level of theoretical und erstand ing of friction mechanisms remains rather low because of a lack of a unified quantum theory taking into account all types of elementary processes occurring in the contact area. So far there is no universally accepted viewpoint regard ing the quantitative characteristics and relative role of electron, electromagnetic and phonon excitation mechanisms, and a cleard ifferentiation is lacking. At the same time it can be said with assurance that there are two types of nanostructural friction: static, ind epend ent of (or weaklyd epend ent on) the velocity, and the ynamic, proportional to the velocity. The microscopic theory of static friction is so far phenomenological in character. Dynamic mechanisms have been stud isd in mored etail, but also call for further examination.

Macroscopic contact mechanics provides an a^{\dagger} equate interpretation of experimental 'friction-load' 'typed' epend encies and the results of measurements of the area of elastic nanocontacts, however, the simple extrapolation of the mechanical properties of materials to the nanostructural level may result in marked errors, since such parameters as the area of a contact, the shearing stress and the ad hesion work may und ergo considerable changes. Besides, contact mod els do not allow one to describe more complex effects associated with atomic and electron structures, chemical composition and microscopic mechanisms, and in the case of friction on the surfaces of alkaline-halod crystals they are not effective at all.

The simple phenomenological (oscillator) \mathbf{mot} el of the SS effecto oes not provir e ao eep insight into the nature of the perior icity of this process in actual experimental practice, when the contact area involves a large number of atoms. A furor amental weakness of this \mathbf{mot} el is that it gives an incorrecto eperor ence of the issipative friction force on the contact stiffness.

The MD method , as applied to problems of nanoind entation and friction, on the whole gives a satisfactory d escription of the energetics, structure and d ynamics of contacts as well as a number of other tribological effects. However, there is a gap between the MD and actual experimental conditions, since in the MD simulation the experiments ultra-short time intervals, the high velocities of nano-probes and restricted statistics of particles are used. Increasing the simulation time (or the number of particles) up to realistic values is fund amentally impossible because of the enormous expenditure of computer time and accumulation of errors when calculating the kinetic energy of particles. This does not allow one to separate correctly the part of energy relating to d issipation. Therefore, the prediction of friction forces for actual experimental conditions when using AFMs still remains problematic. In this connection the d evelopment of quasistatic-type mod els based on the ad hesive theory of bond breaking is a topical problem.

As to the d ynamic mechanisms of friction, it should be noted that they all, d espite existing d istinctions, give (in the case of AFM) closely relater values of friction forces of the of t er of 1 pN at probe velocities of about 1 m s⁻¹. In QCM and SFA experiments and in the modulation mode of AFMs, this mechanisms may play an important role, therefore, there is a next to perform tail calculations of friction forces for concrete conditions. The presence of specific (for d ifferent mechanisms) d eperd encies of friction forces on the probe ratius, temperature and other physical parameters of tribocontacts provides a possibility for a critical choice between available mot els by measuring numerical d ecrements in the vibration more of an AFM as well as provering the basis for the evelopment of new nor estructive method s for the d iagnostics of nanostructural parameters. In the case of QCM experiments, the observer d amping time may be ở eterminer byở ifferent effects, therefore, it is also necessary to compare theoretical end experimentald ata.

5. Technological applications

As is evit ent from the foregoing, the nanotribological aspects of the problem of contact interaction are connected with a broat spectrum of physical and chemical properties of surfaces and play a key role in many application areas, among which the following areas should be primarily noted: prot uction and exploitation of magnetic record ing d evices; d evelopment of new surface coatings and mod ification of their tribological characteristics; nanolithography; mechanical engineering; chemical prod uction; d iagnostics of physical properties, composition, structure and relief of the surfaces of materials and so on.

In magnetic record ingd evices one of the most important problems is the fabrication and d iagnostics of the properties of protective coatings with the aim of increasing their reliability and extending their life. Bhushan et al. [87] were the first to lay a fourd ation for application of AFMs for conducting technological and tribological tests of magnetic tapes, hat disks and different protective coatings. The authors of work [24] d eveloped a d epth-sensitive technique for multiple slip nanoind entation of surfaces making it possible to perform a quantitative comparison of the tribological characteristics of filmsd eposited onto substrates of the same type. For the material interface in contact record ing d evices, surface d egrad ation is the most serious problem. Triboelectromagnetism, causing the d isruption of the molecular structures of lubricating coatings, is another severe problem. For these reasons in recent years in the magnetic ind ustry preference has been given to d isk sld ers

operating in the tapping $\mathbf{m}\mathbf{\sigma}^{\mathbf{i}} \in [103]$ in which a stiff contact with a surface takes place only at the instants of the start $\mathbf{a}\mathbf{\sigma}^{\mathbf{i}}$ stop of slip er motion. In prospect, however, the implementation of the contact $\mathbf{m}\mathbf{\sigma}^{\mathbf{i}} \in$ will make it possible to increase considerably the writing density, the rate $\mathbf{a}\mathbf{n}^{\mathbf{i}}$ quality of writing $\mathbf{a}\mathbf{\sigma}^{\mathbf{i}}$ read ing.

Method s for combatting wear of the components of instruments and machines using the ion-plasma and ionstimulated treatment of surfaces call for comprehensive information on wear mechanisms: abrasive wear, ad hesion, material fatigue, erosion and fretting-corrosion. In practice, d ifferent combinations of these mechanisms, as a rule, are observed. For example, tribological problems relating to the wear of the components of mill machines used for crumbling plastic materials are concentrated around the processes of ad hesive friction and d egrad ation of surfaces, abrasive wear by the flow of crumbled materials, corrosion of instruments stimulated by gases and the prod ucts of plastic d ecomposition. The d iscussion of these and many other aspects of present d ay ind ustrial tribology can be found in work [120].

In the last ecat e const erable attention has been given to the probing mot ifications of surfaces as a method of nanolithography (see work [90] and the literature cited therein). Contact of the STM tip with the passivater surface of a silicon plate in uces its ox ation, therefore, the process of fabrication of photomasks may be accomplished in the mot e of contact interaction of the probe with the surface. There are several factors making this technology attractive: ultra-high resolution, the accuracy of accommodation and orientation of relief d etails as well as high throughput. However, in of er that this technology becomes commercially profitable, the scan velocity in the 'scratch' mot e must be raised up to 1 cm s⁻¹. In presented ay commercial AFMs the velocities are three-four of ers of magnitude lower. Hence, there is a neet to investigate nanostructural friction over a with er interval of velocities.

Another technological line in nanolithography may open the way to noncontact ion mot ification of materials using nanobeams focuser onto a surface by nanowires connecter with the bracket of a scanning probing microscope [121].

Simulation of the d ynamic characteristics of thin-film lubricating coatings occupies a highly important place in the solution of a rich variety of technological problems ranging from the problems of elastic hyd rod ynamical lubrication of toothed gearings and slip bearings to the tribology of the next generation of storage d evices. Simulation allows one to rod uce the existing gap between technical friction and nanotribiology and refines the theoretical und erstand ing of the mechanisms of materiald egrad ation.

The possibilities of commercial use of nanostructural friction for activization of the process of tribochemical wear $an^{\hat{T}}$ the self-organization of molecular complexes on friction bound aries still call for further investigation.

At the present time there can be little $\dot{\mathbf{c}}$ oubt that the classical friction coefficient and the velocities of material wear on the nanostructural level are less than those on the macrolevel, whereas had ness, on the contrary, is higher. Hence, the operation of the future generation of micromachines may have peculiarities which cannot be predicted on the basis of simple similarity notions [4]. Nanotribological investigations with the use of AFMs $\dot{\mathbf{c}}$ on the allow one to predict uniquely the values of macroscopic friction and wear coefficients, since the $\dot{\mathbf{c}}$ irect proportionality between the friction force and the load ing force results from overlapping

and interaction of the numerous microcontacts of surfaces, their elastic and plastic d eformation, vibration smoothing and so on. Nevertheless, test investigations of the d egrad ation and wear of surfaces because of friction cond ucted using the AFM method, which allows one to control the process of nanoind entation, have become an ind epend ent method for the engineering i agnostics of material surfaces and d etermination of a wide range of their physical and chemical properties.

6. Conclusions

The rich variety of experiments and theoretical models considered in the review demonstrates the considerable potential of nanoprobing microscopy and gives notions of the spectrum of available experimental and theoretical problems relater to nanotribology. Progress in their solution and the practical implementation of the results of investigations will depend on the improvement of experimental equipment and the quality of new informations obtained in experiments, on the one hard, as well as on the efforts of theorists, on the other. Nevertheless, even tot ay one can speak of the formation of a new promising line of surface physics-nanotribology. The most d ramatic result of these investigations is the achiever possibility of measuring ultrasmall forces between a nanoprobe and surface atoms. The simplicity of the probing element itself is worthy of at miration: it is a mere sharp jut (hair) on the console, whose d eformation is d escribed in add ition by one of the simplest physical mot els — the harmonic oscillator mot el! However, nanotribology cannot be constructed a particular line of investigation associater only with the use of AFMs. In combination with nanoin entation - vertical probing, nanotribological investigations allow one to study the atomic structure of matter in three d imensions and not only to measure, but also to see it. This was und reamed of only a few years ago, and tot ay this ream has been realized.

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